

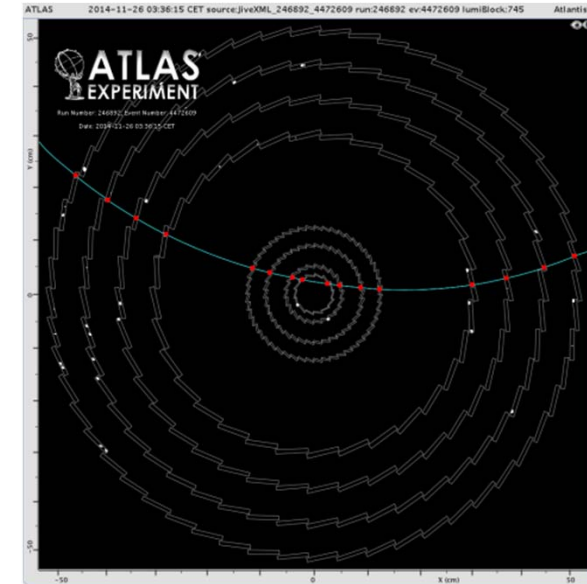
Journées VLSI 2016

Configuration Column Chip (C3) en 65nm TSMC

(et activités **pixels** au LAL)

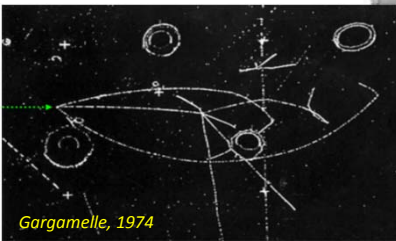
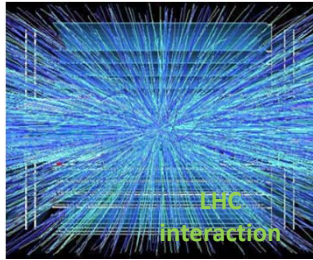
Maurice Cohen-Solal, Mowafak EL Berni,
Olivier Lemaire, Philippe Vallerand

LAL – Orsay Université Paris-Saclay



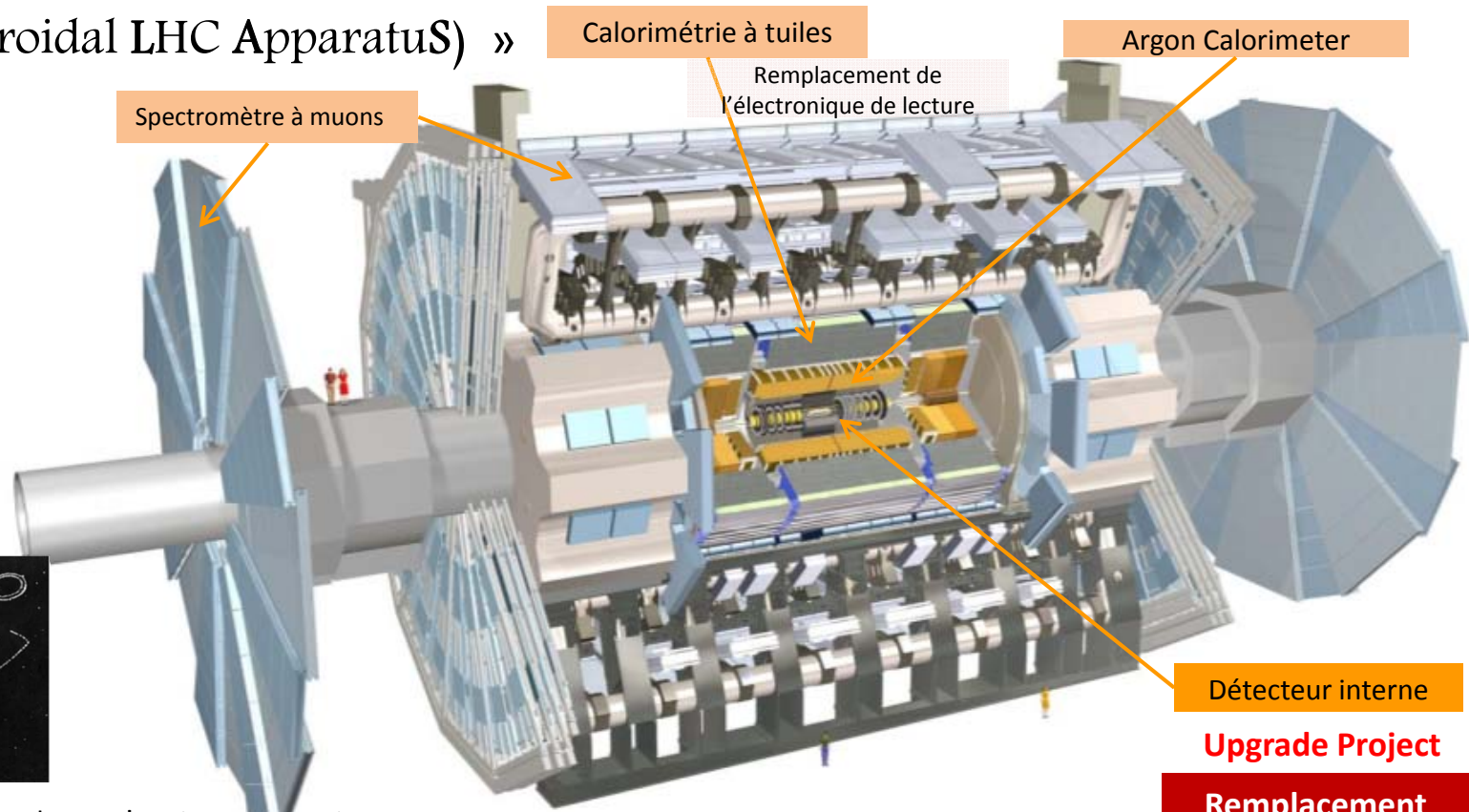
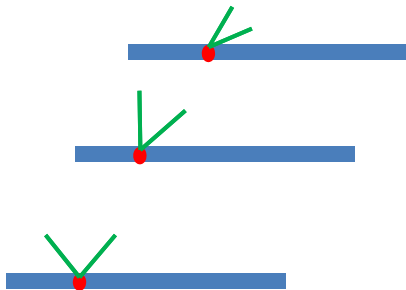
« ATLAS (A Toroidal LHC ApparatuS) »

Contexte



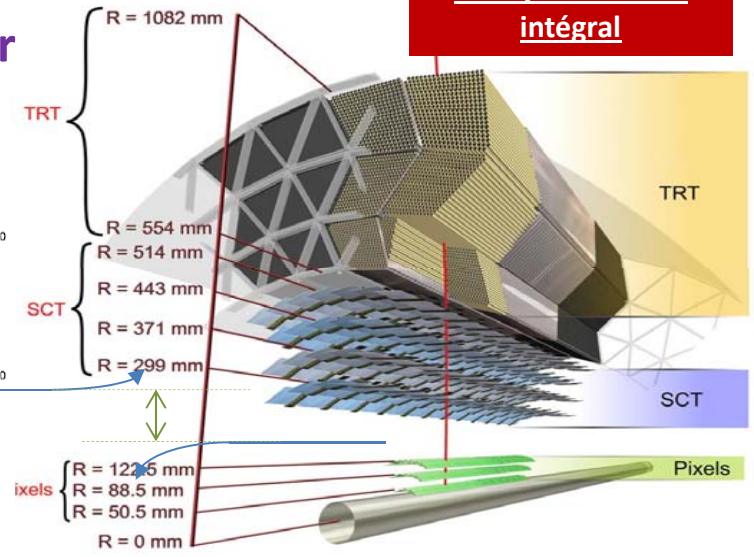
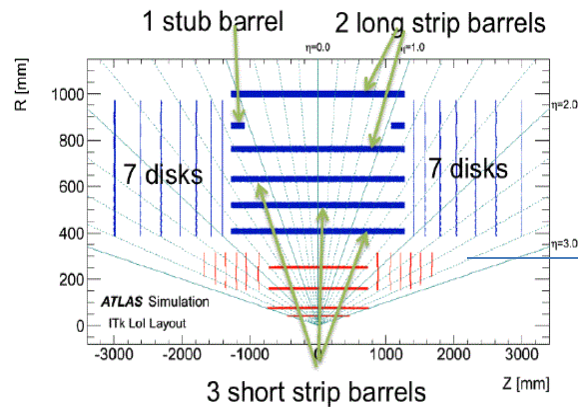
- Localiser les vertex (3 dimensions)
- Haute résolution en $r.\phi$ ($50\mu\text{m}$)
- Paramètres d'impact ($15\mu\text{m}$)

détecteur de positions → tracking



Upgrade Project
Remplacement intégral

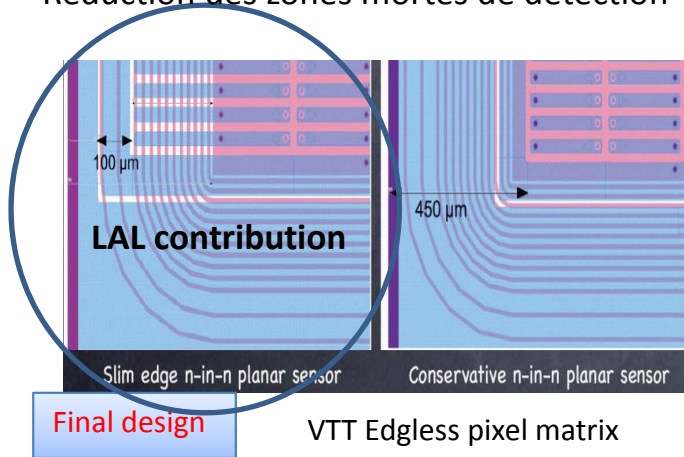
Tracker



Sensor \propto irradiation

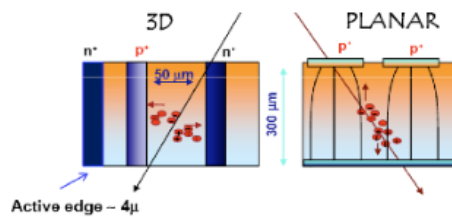
Anneau de garde

Reduction des zones mortes de détection



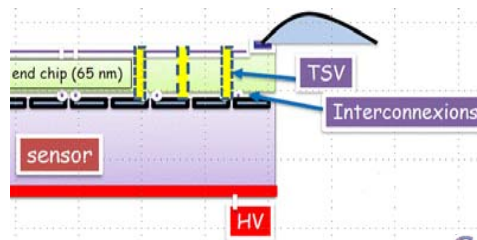
VTT Edgless pixel matrix

(R&D ligne de champs)



(R&D amplification)

«LGAD» (RD50)

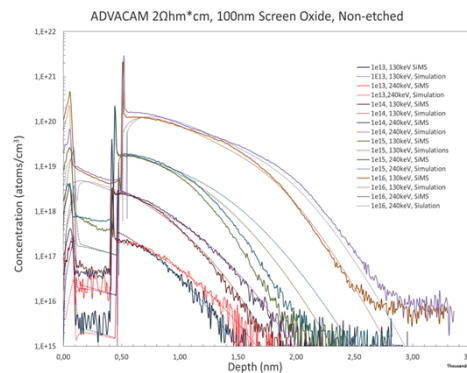
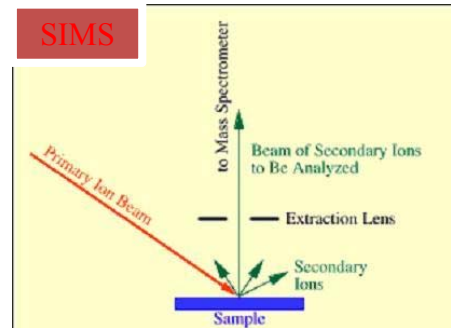


Instead of wire or bump bonding, TSV could be considered in chip periphery for improved the time transit.

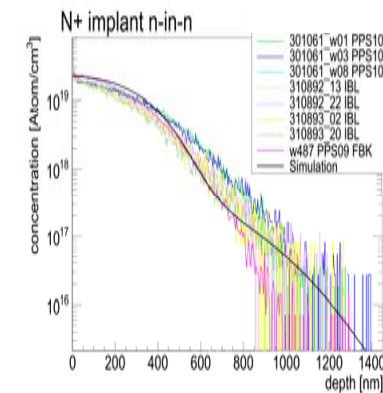
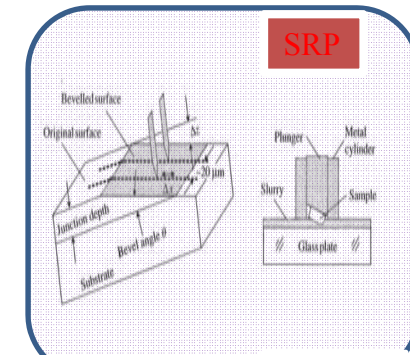
(Collaboration with the LETI-Grenoble)



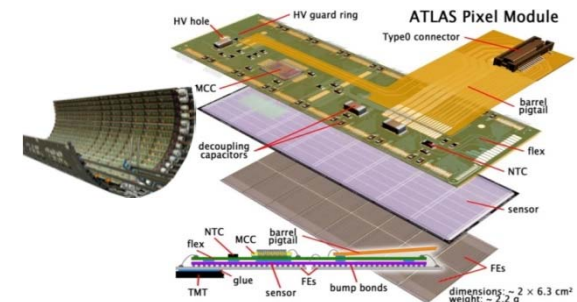
Profils de dopages



Secondary Ion Mass Spectrometry
(concentration de dopants vs profondeur)



Spreading Resistance Profiling
(concentration de porteurs vs profondeur)



3 dimensions

Omégapix2

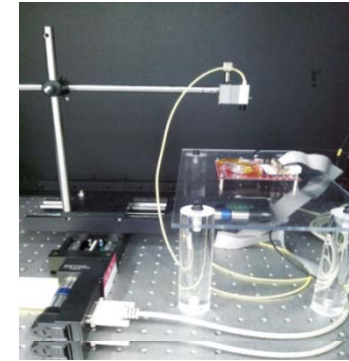
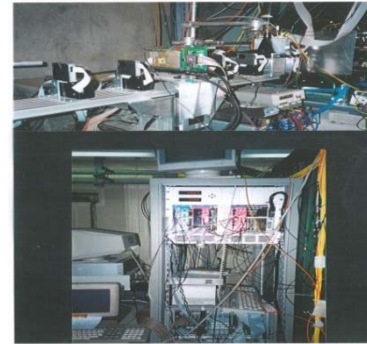
(130nm)

Pitch : 35 μm x 200 μm

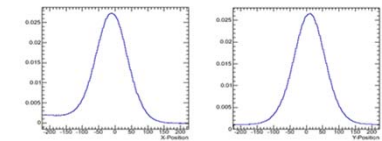
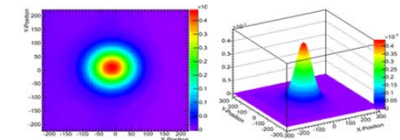
96 x 24 = 2304 pixels



BEAM TELESCOPE



Laser Testing Station



Beam Shape

2D



Global Foundries

3D

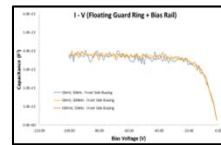


TSV Tezzaron process

Full



VTT
Leti connexion

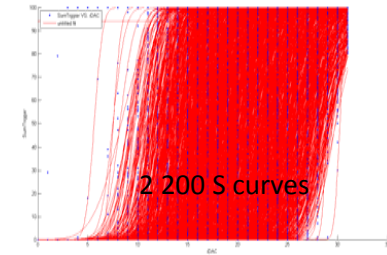
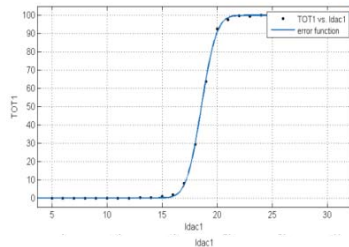
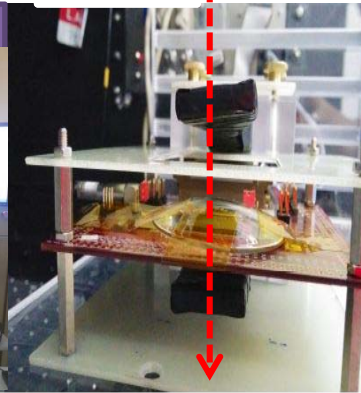


Si Pixel cosmic bench

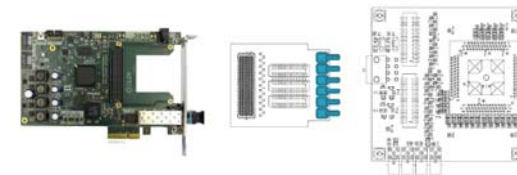
Source



Measurement from -60 °C to 300 °C



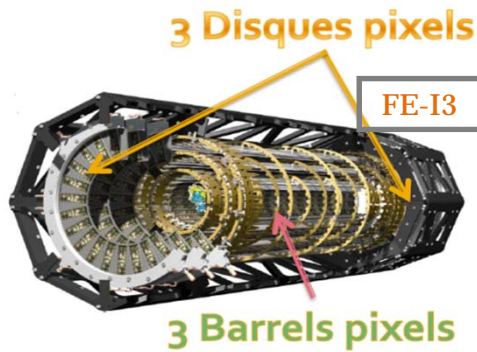
Nouveau système d'acquisition



Carte SPEC + M-LIB + Front End

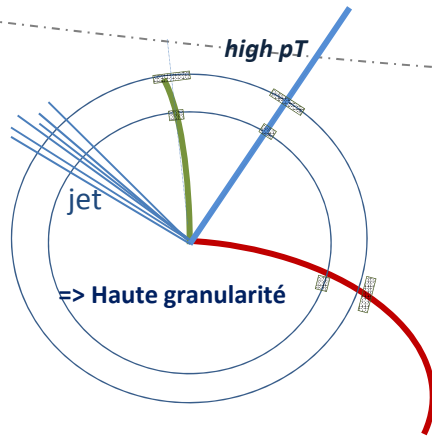


LHC-HL « Upgrad » (2025)

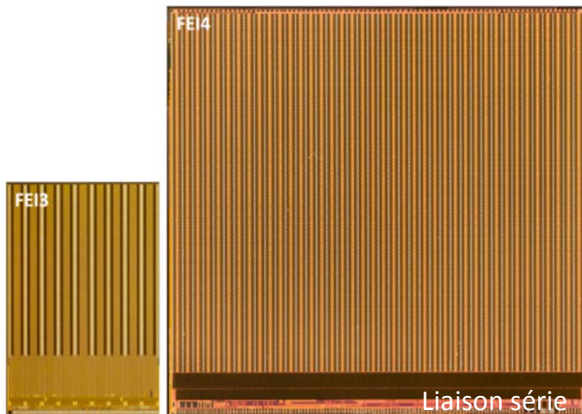


Present beam pipe & B-Layer

FE-I4



5 ATLAS pixel institutes



Fréquence collision 40 MHz \equiv 25 ns

FEI4 compared to its predecessor FEI3

	FEI4B	FEI3
Year	2011	2003
Technology	130nm	250nm
Chip size	20x19mm ²	7.6x10.8mm ²
Active area	89%	74%
Array	80x336 (26'880)	18x160 (2'880)
Pixel size	50x250μm ²	50x400μm ²
Number of transistors	87M	3.5M
Data rate	320 Mb/s	40Mb/s
Wafer yield	60%	80%

5 (7?) couches de pixels \sim 180 m pixel

(début production 2022) :

Array : = 134,400 pixels
pitch : 50μm x 50μm

Puce \sim 20 mm x 20 mm (\sim 10⁹ transistors)

400 colonnes x 400 lignes

Hit \sim 2(3) GHz / cm²

3 Gb / s / chip (actuellement 10 fois moins)

1 Watt / cm²

L1 Latence \sim 10.5 μs (actuellement 3μs)

Trigger: 1MHz

Luminosité 7x LHC = HL-LHC = 7.10³⁴cm⁻²s⁻¹

10¹¹ protons par paquet

\sim 190 événements (interactions) par Beam Cross

(actuellement 24)

Radiation 10MGy = 1 GRad (actuellement 200MRad)

10¹⁶ neq/cm²

RD 53 Collaboration :

Development of pixel readout integrated circuits for extreme rate and radiation

➡ Design the next generation of pixel readout chip

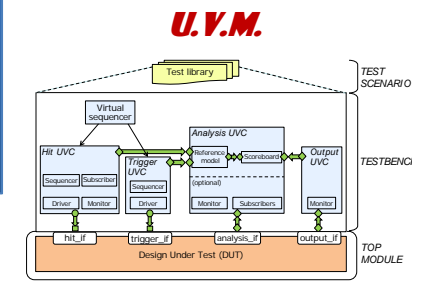
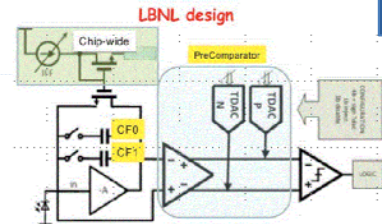
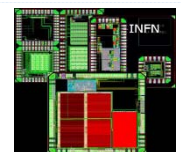
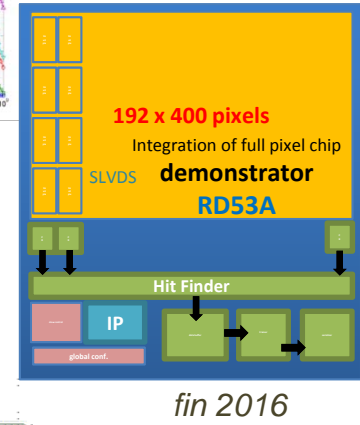
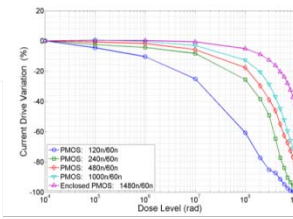
for futur HEP experiment (ATLAS & CMS phase 2, ...)

Challenges : smaller pixel size (density), higher hit rates, radiation tolerance, faster readout.



Proposal **accepté sept.14**
Guest (Jan 15)

- Working Group
- WG1 : Radiation (*Marlon Barbero*)
 - WG2 : Top Level Design (*Maurice Garcia*)
 - WG3 : Simulation Test Bench (*Tomasz Hemperek*)
 - WG4 : I/O (*Roberto Beccherle*)
 - WG5 : Analog Design (*Valerio Re*)
 - WG6 : IP Blocks (*Jorgen Christiansen*)

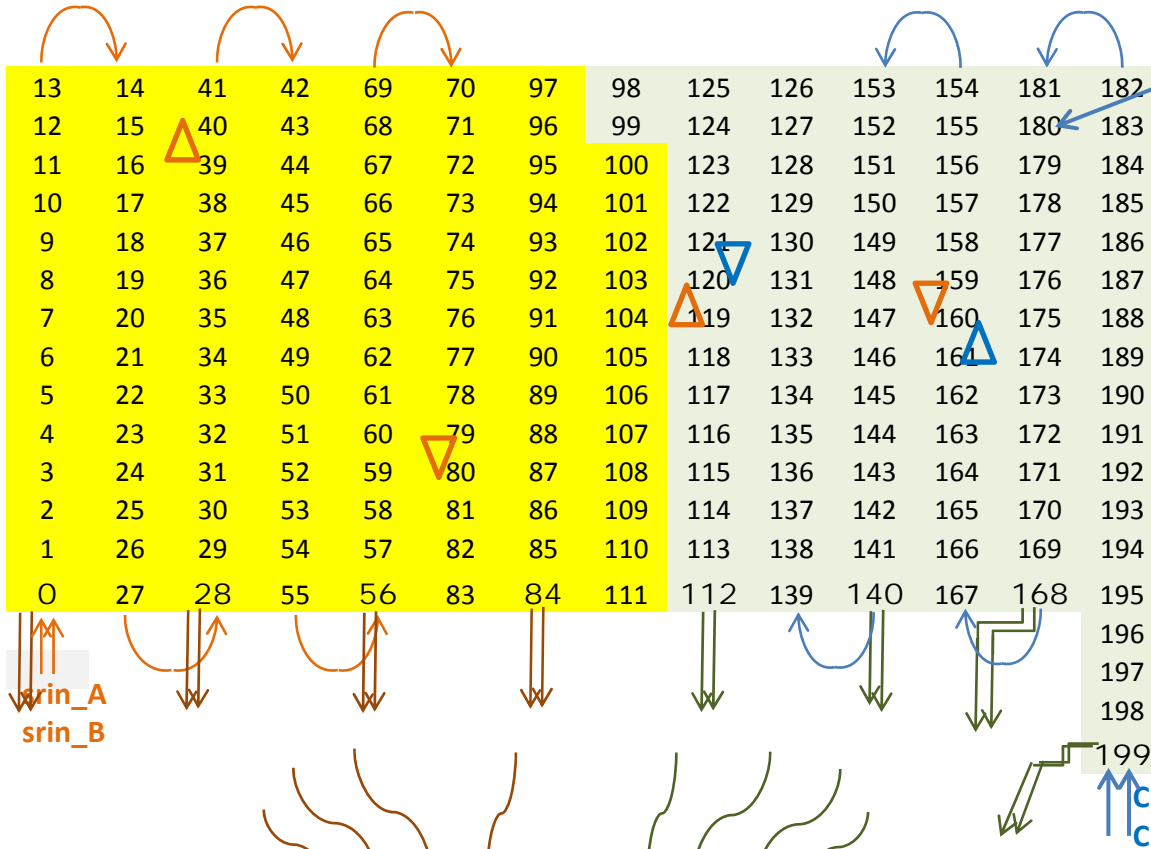


LAYOUT = 1/2 COLUMN OF 200 PIXELS

1 mm x 1 mm au pas de **50µm x 50µm**

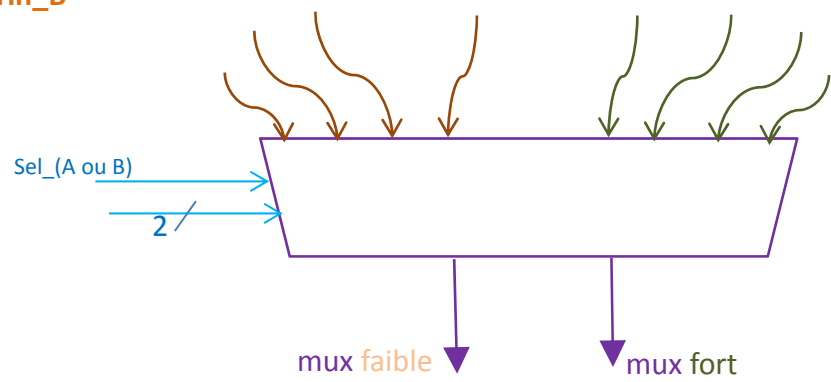
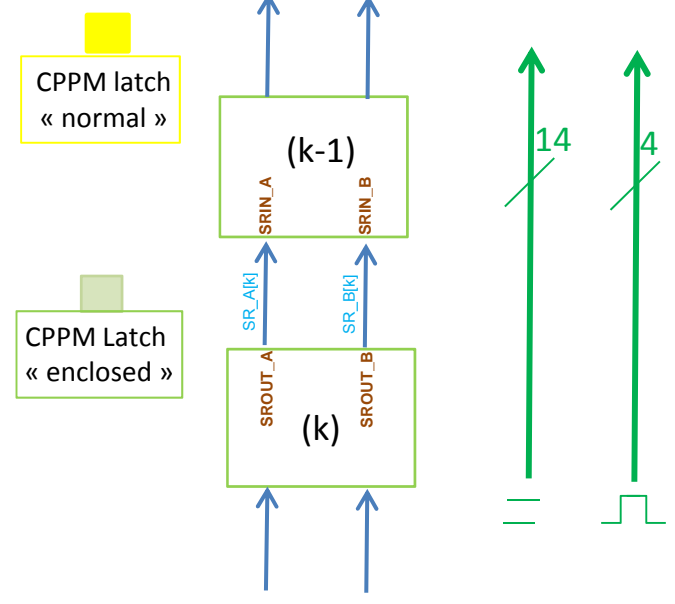
serpent

(design 14 x 14 + 4 cells **chained**)

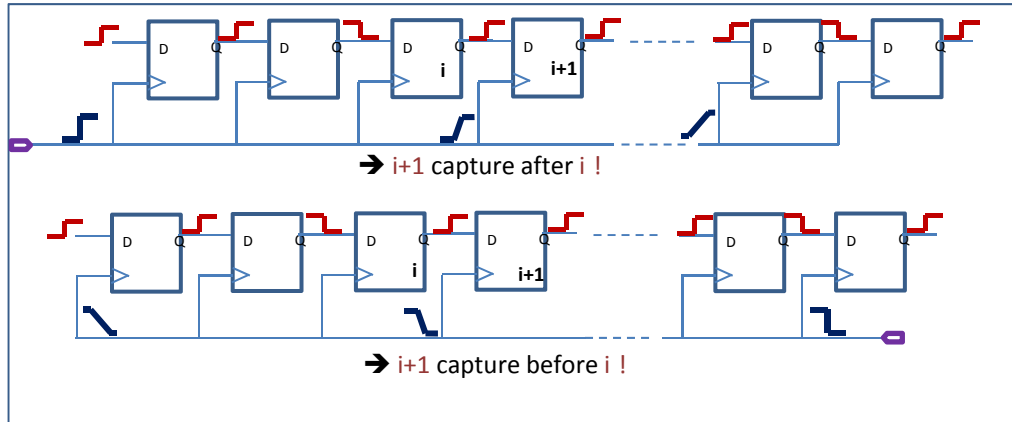


Configurations

- [0]: output enable (hit-en)
- [1:5]: Threshold_DAC
- [6]: large injection capacitor
- [7]: small injection capacitor
- [8:11]: TOT_DAC



CPPM recommandation :



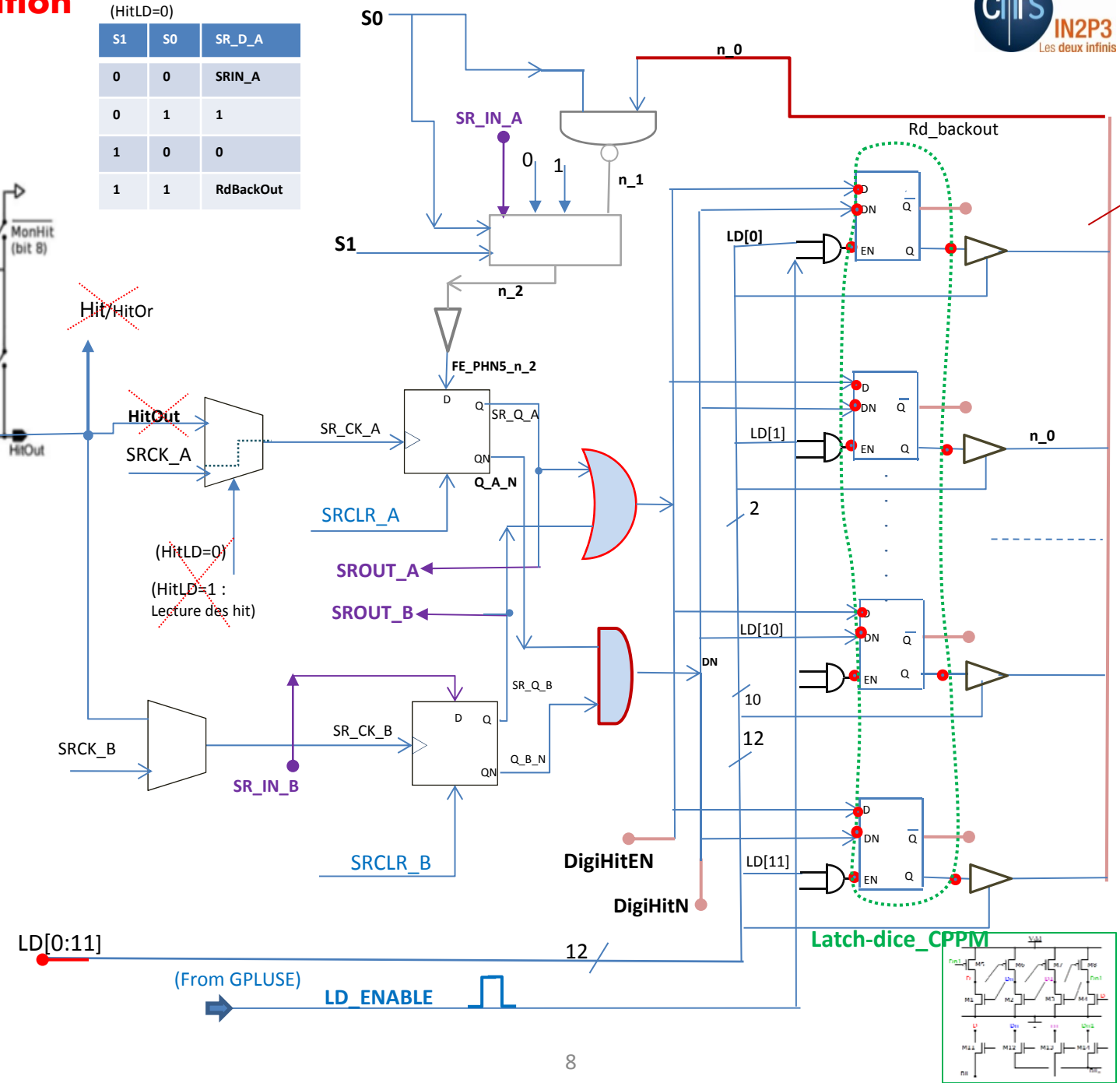
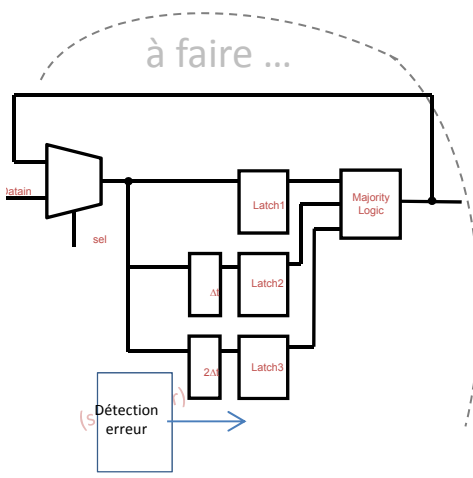
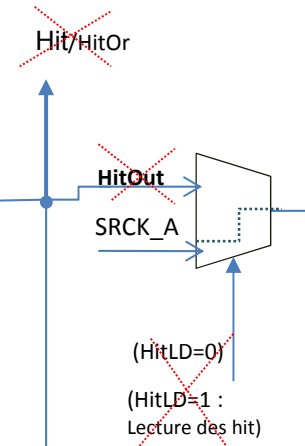
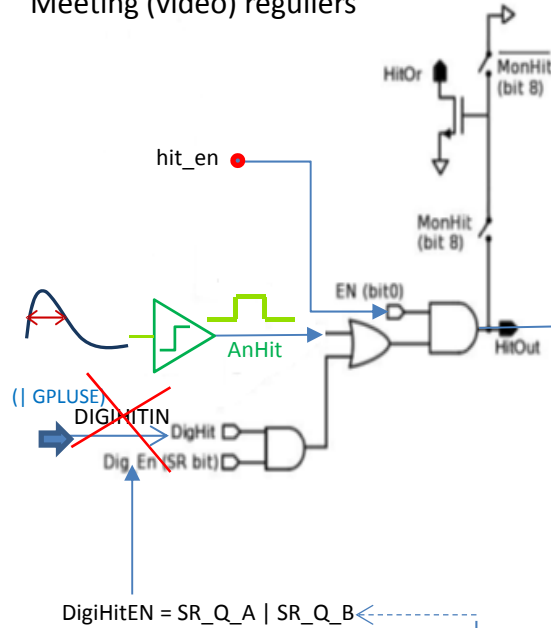
One pixel configuration

Collaboration avec CPPM
Marseille (dec.14- oct.15)

Moshine Menouni & Denis Fougeron
Meeting (vidéo) réguliers

(HitLD=0)

S1	S0	SR_D_A
0	0	SRIN_A
0	1	1
1	0	0
1	1	RdBackOut

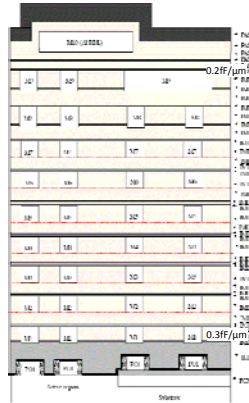


65 nm
 9 layers stacks :
 (for routing)

Supply Voltage 1.2V

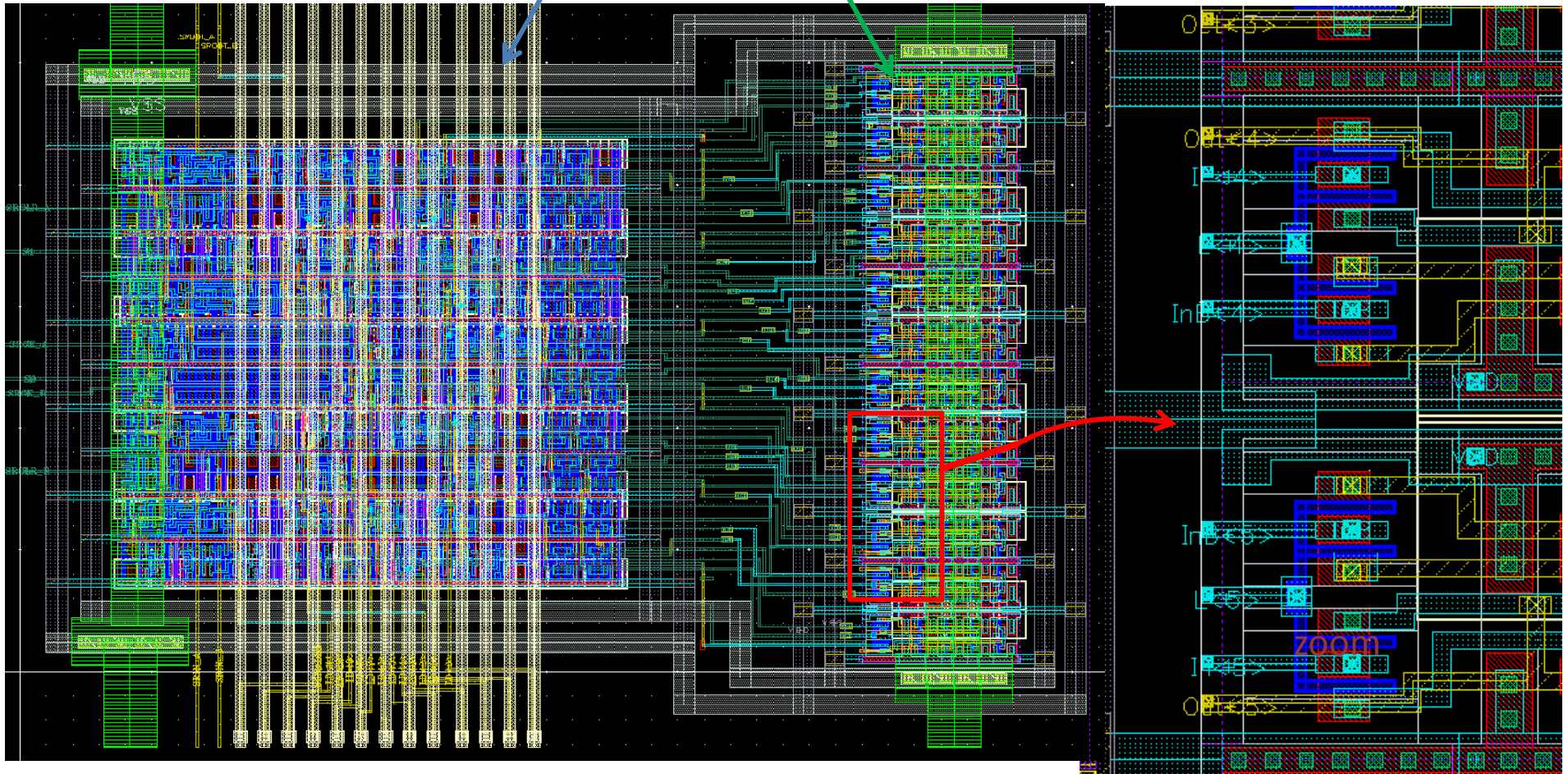
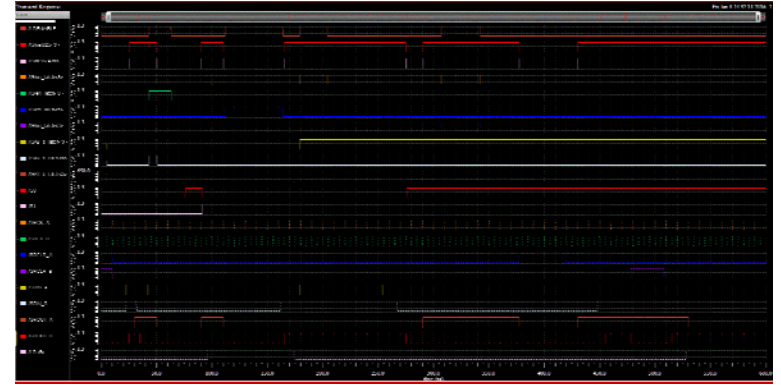
Vth = 0.450 V

encembrement
 $\frac{1}{4} (2500) = 625 \mu\text{m}^2$



Config one pixel (12 bit)

LAL – CPPM

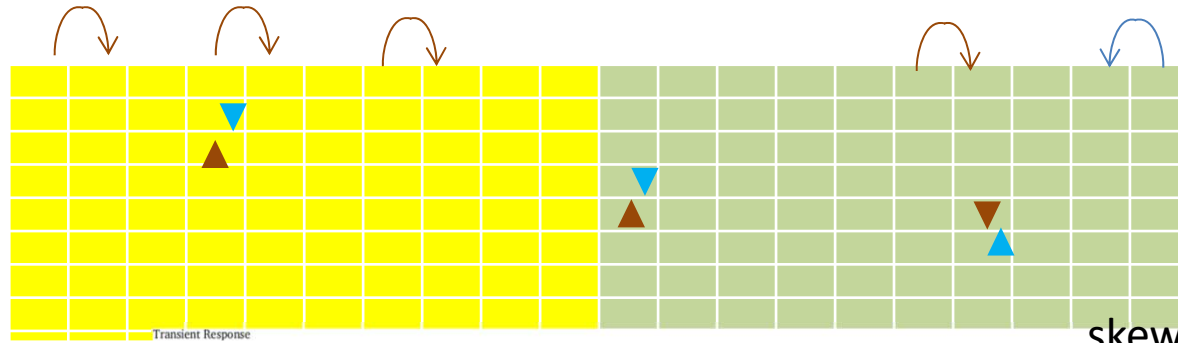


Configurateur : $20.73 \times 19.5 = 404.2 \mu\text{m}^2$

1 Radhard latch 12 bits = $10.35 \times 29.32 = 303.5 \mu\text{m}^2$

Optimisation buffers & lines pour 1 column de 400 pixels

LAYOUT = 20 LIGNES X 20 COLONNES = 400 PIXELS 1 mm x 1 mm pitch 50µm x 50µm



Clock : length line
400 x 50 µm = 20 mm !

Correction cellule dans le code synthétisé

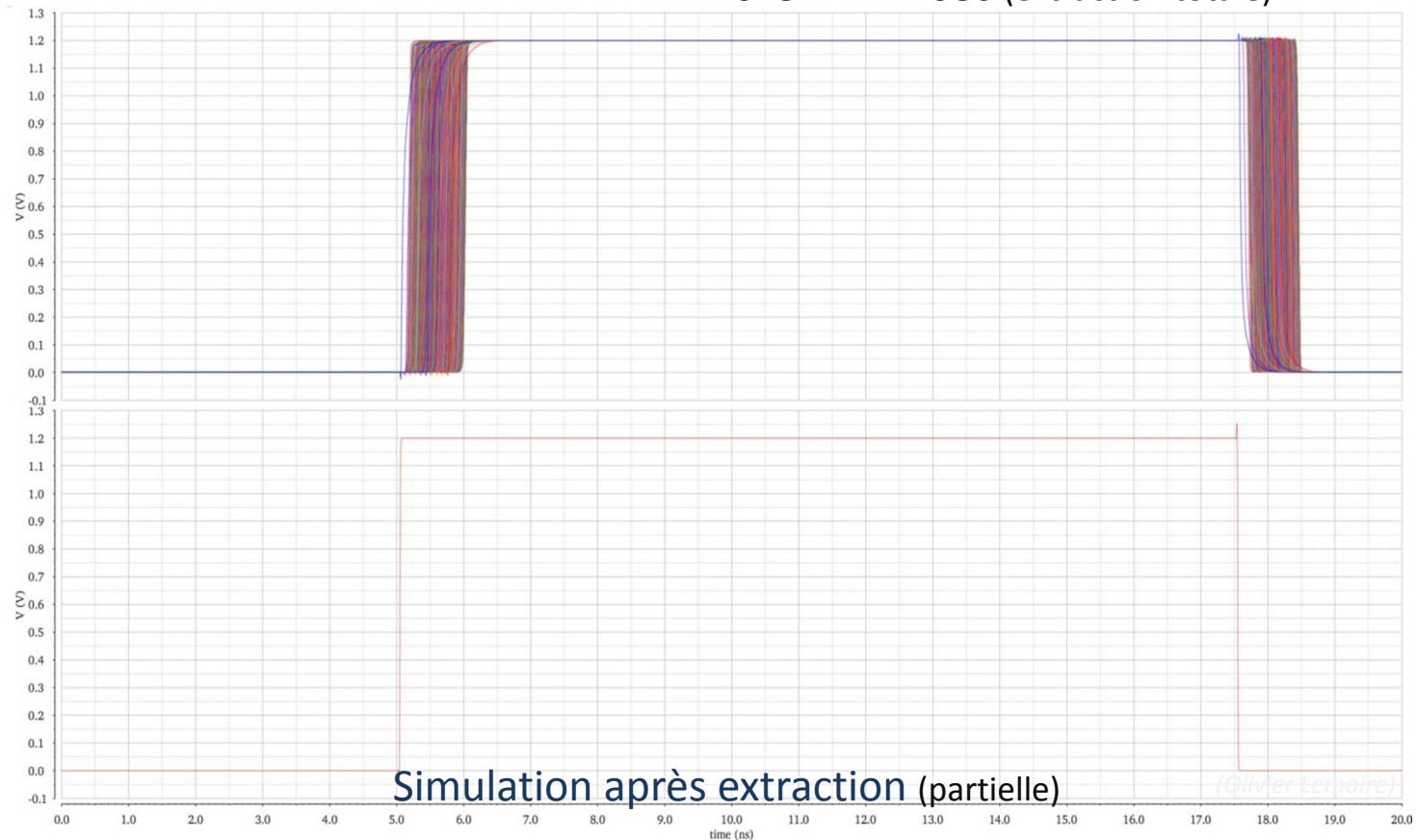
skew = 2 nsec (extraction totale) Wed Feb 24 16:05:14 2016

Optimized under Virtuoso

Do not use higher metals
(too width)

Optimum found :
buffer each 40 pixels

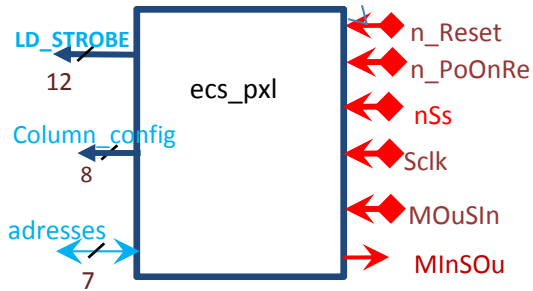
(The buffers are inside the pixel)



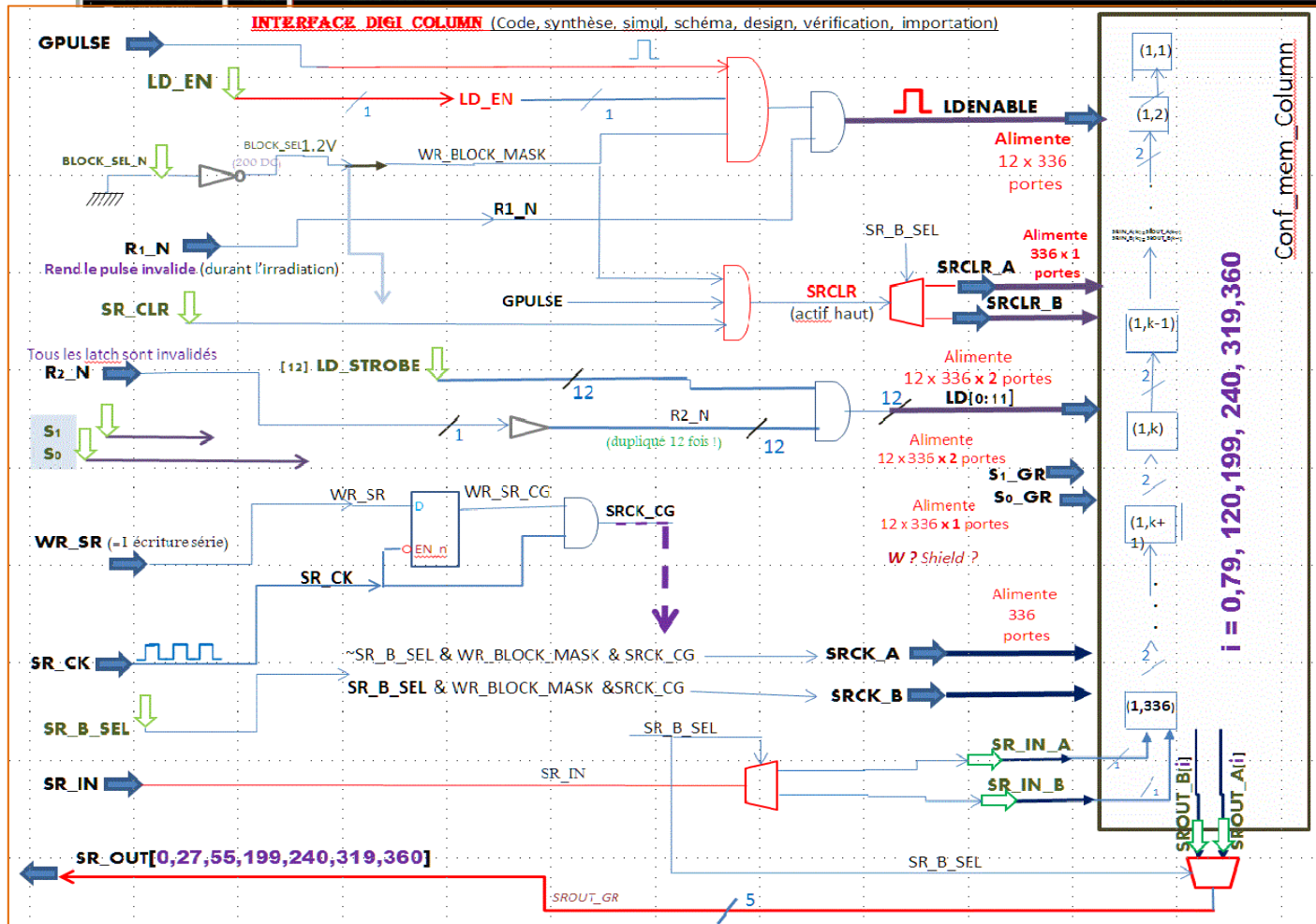
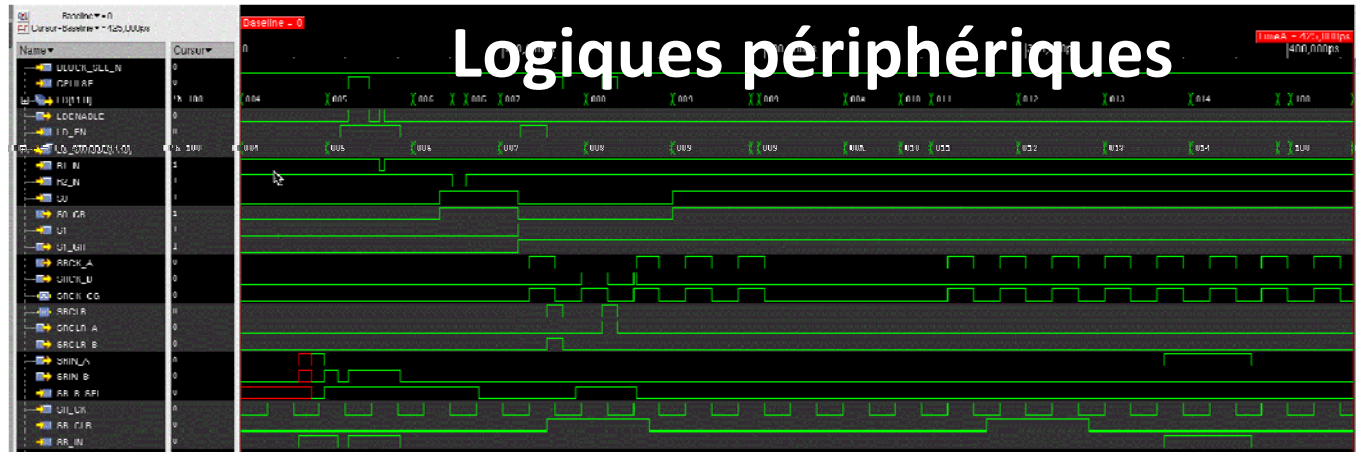
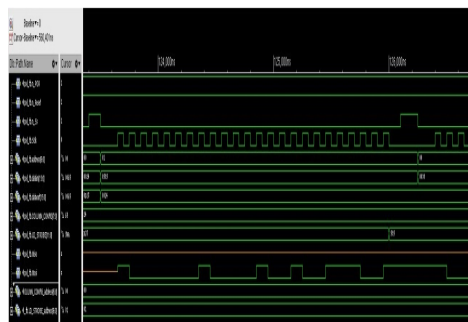
Simulation après extraction (partielle)

(@Olivier Lemaire)

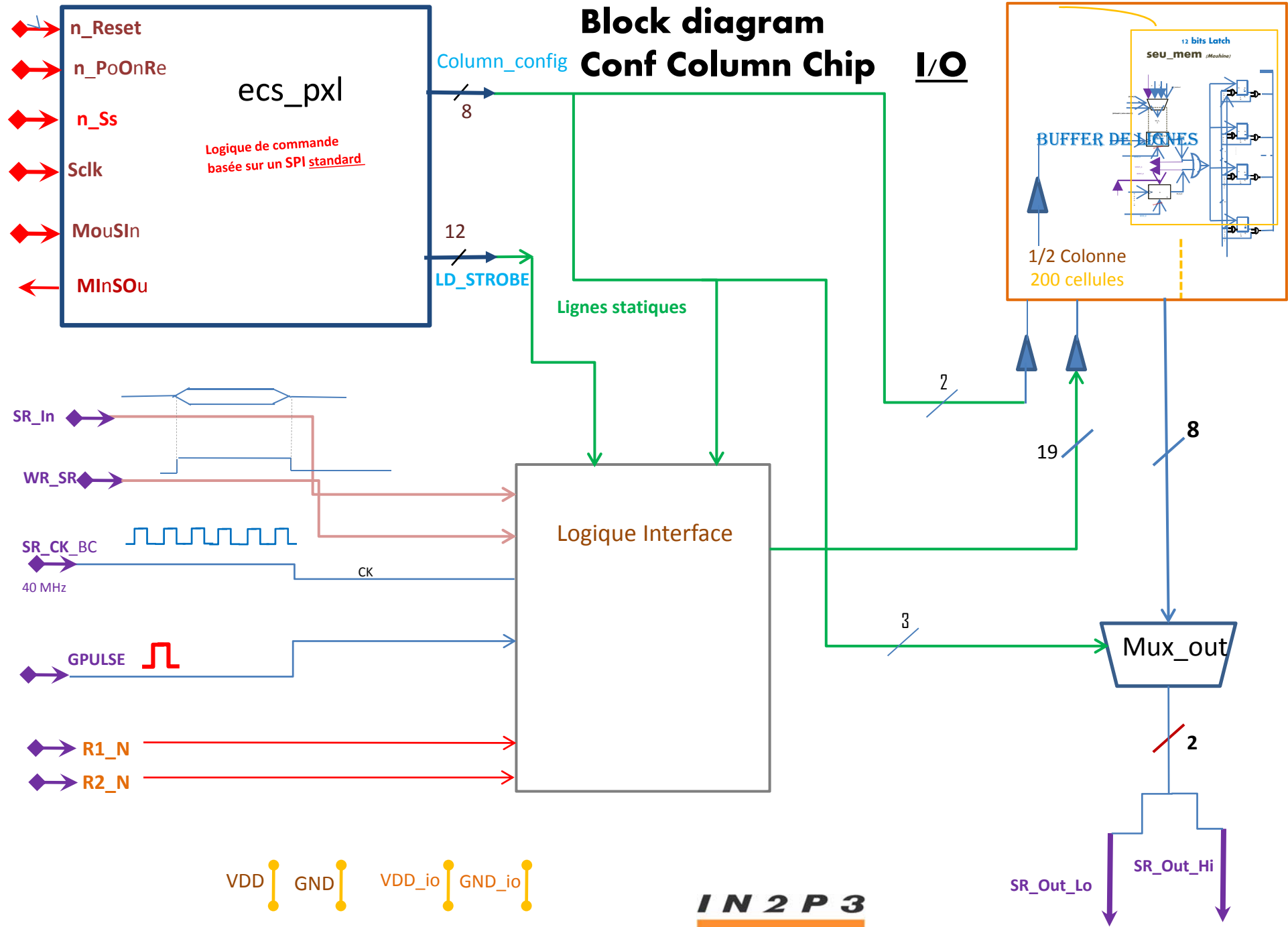
encapsuled_pixel



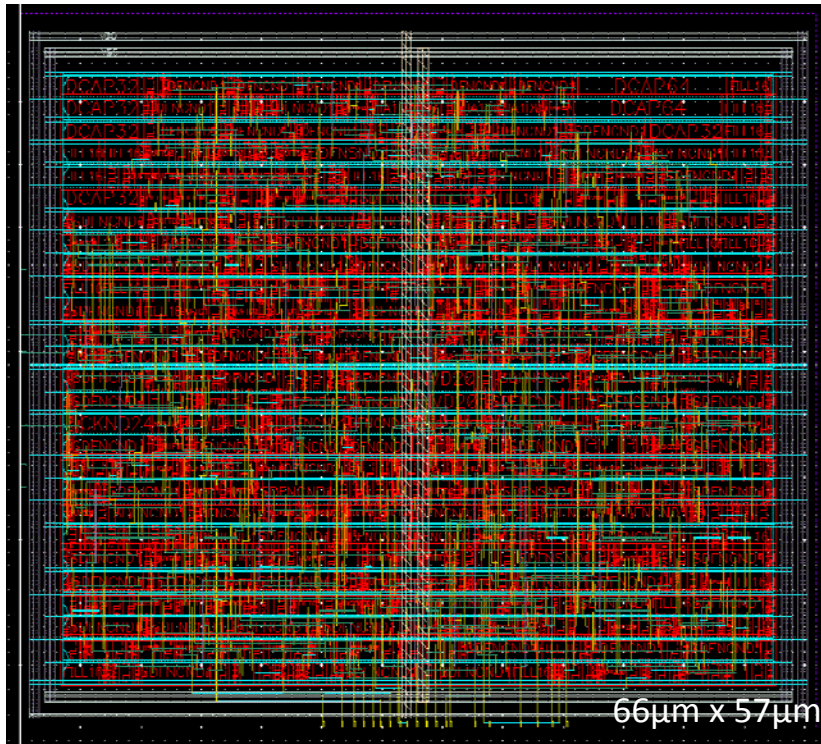
Basé sur un SPI
(triple voting)



Block diagram Conf Column Chip I/O

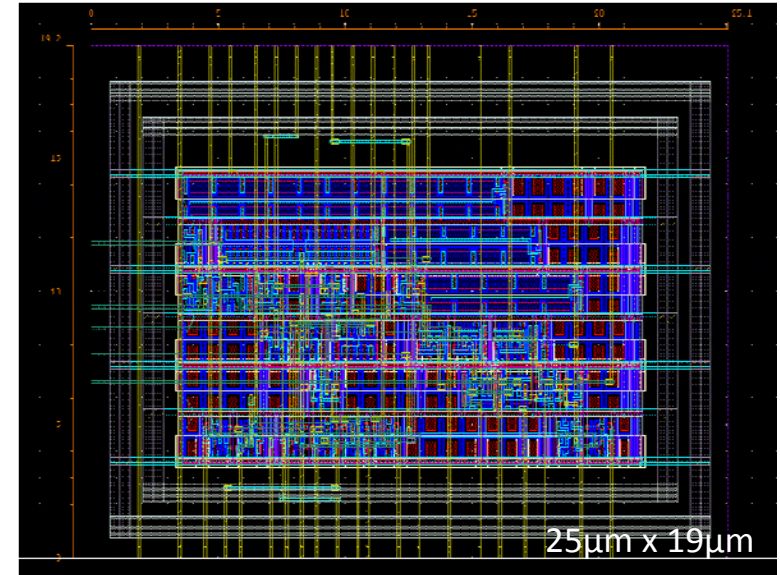


Blocks périphériques

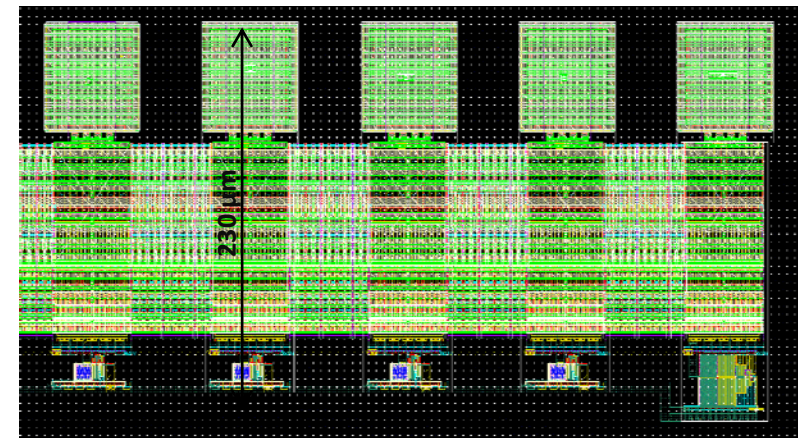
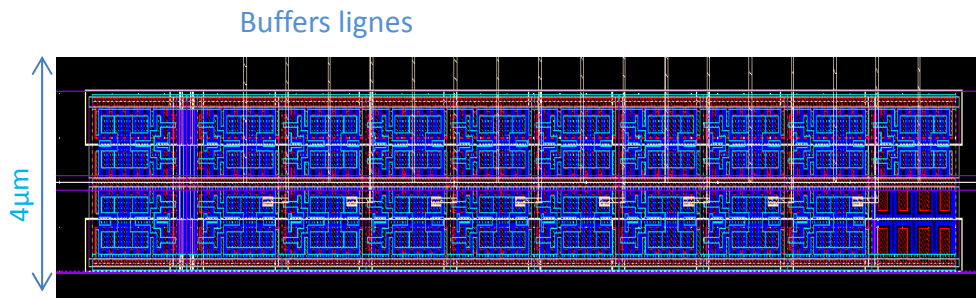


1.2 Volt

Encapsulé SPI



Logique d'interface



Top level integration :

« Génération matrice automatique »

Blocks simulation : spectre

Top level simulation : AMS & behaviour

Coût

- **MPW – Multi-Project Wafer**

price ~ 90% engineering run (Full Maskset)

Mini ASIC 2mm x 2mm = 17 000€ + 1 000€

(C3) → 1 mm x 1mm = ¼ (18 000) = **5 150 €**

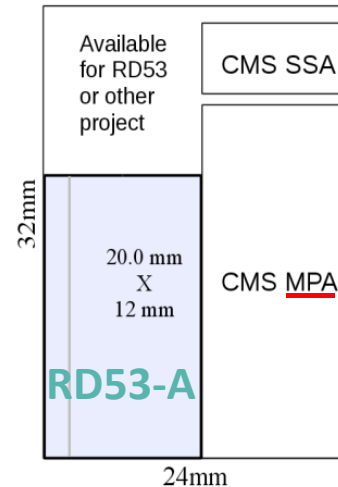
(RD53-A) → 20 mm x 12mm ~ **500 k€**

- **MLM – Multi Layer Mask (Reticle)**

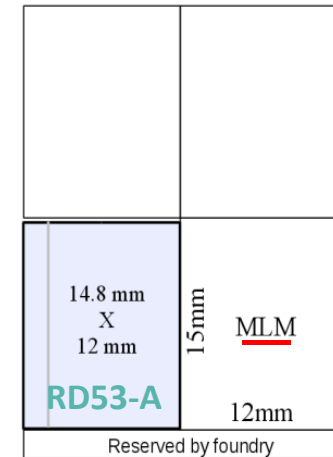
NRE (Non-Recurring Engineering)

220 k\$ / mm²

wafer price



(fin 2016)



Back-up solution

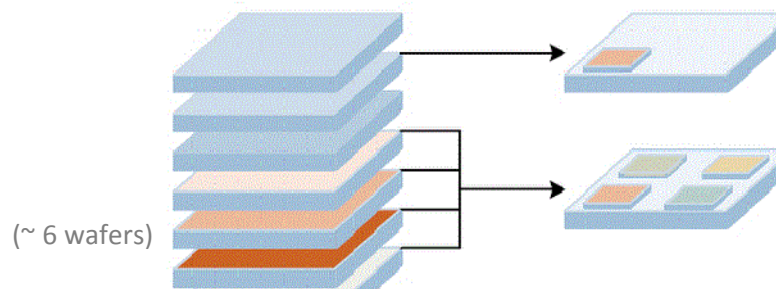
- **Engineering Run**

(RD53-A) → 20x12 mm² ≅ ~ 1 M€

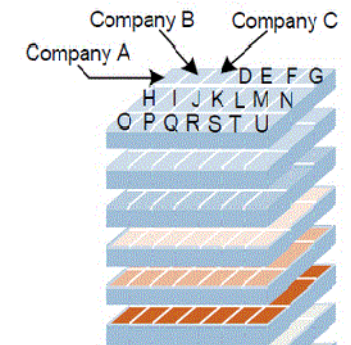
(RD53) → 400 mm² ≅ 2,2 M€

Full MaskSet

MLR



(Shuttle Run)



Conf Column Chip (C3)

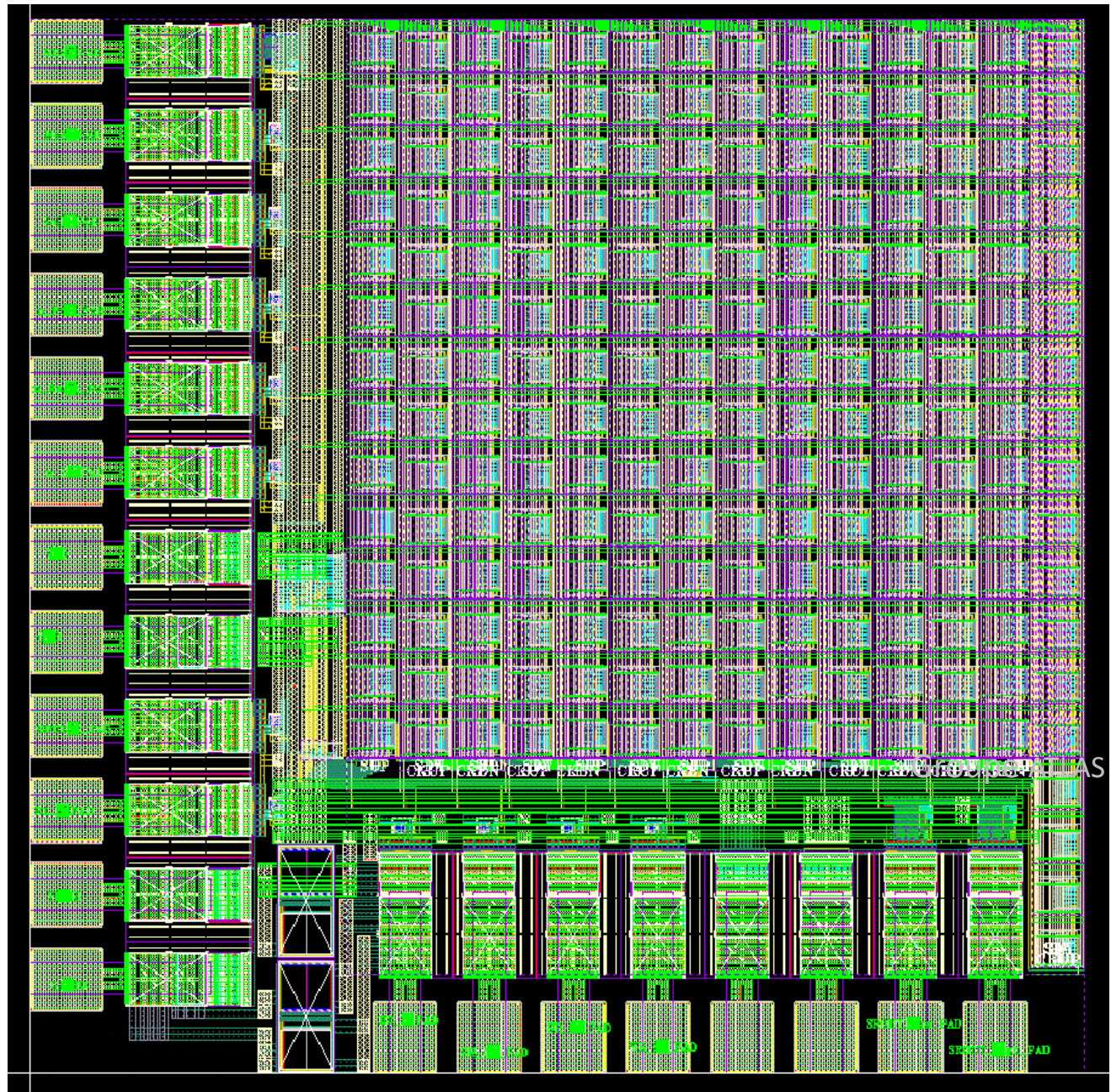
Layout « top level »

- Size 1 mm x 1 mm
(pitch $50\mu\text{m} \times 50\mu\text{m}$)

- PADs on 2 sides

14 x 14 + 4 pixels

Submitted
on 23rd march

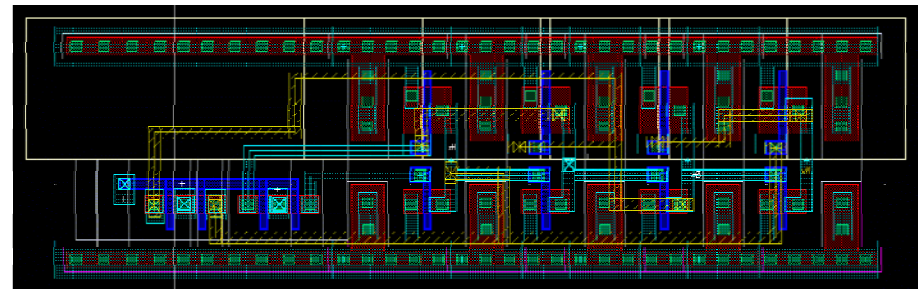


Futur développements

26 avril 16 : présentation au meeting RD53-A

- Reprendre le Rad Hard Latch
- Reprendre la cellule (CPPM & [RD53-A](#))
- *Implémentation Triple Module Redundancy*
- Implémentation cellule dans RD53-A
- **Universal Verification Methodology** *Verification Environment for RD53 PIXel chips*
Simulation consommation et SEU de la configuration d'une colonne

- *Cartes de test*
- *Firmware, software*
- **Test irradiation**
(Set-up, hardware, software, formation, suivi médical, accès)



Zone contrôlée



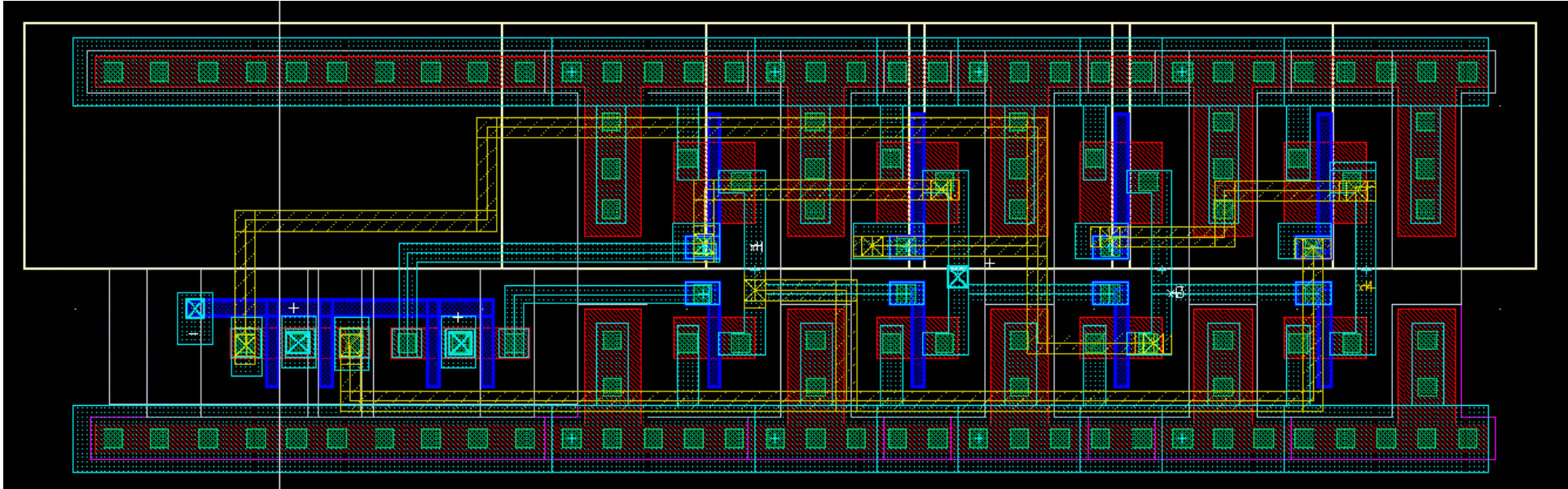
Backup slides



IN2P3

INSTITUT NATIONAL DE PHYSIQUE NUCLÉAIRE
ET DE PHYSIQUE DES PARTICULES





IN2P3 dans ATLAS tracker Phase-II Upgrade

Pixels:

CPPM(Marseille), LAL(Orsay),
LAPP(Annecy), LPC(Grenoble), LPNHE(Paris)

Fast Tracker:

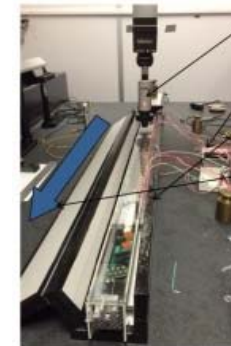
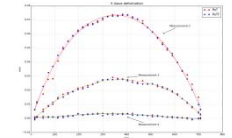
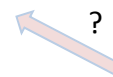
LPNHE(Paris)

Pixel microélectronique :

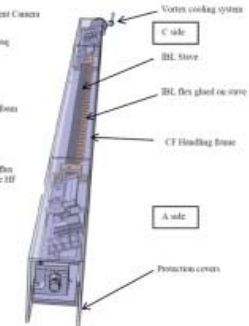
CPPM(Marseille), LAL(Orsay), LPNHE(Paris), ?

→ Réunion des 3 laboratoires

Représentation dans RD53 : LBNL, SiLab, CERN, INFN,



Mécanique



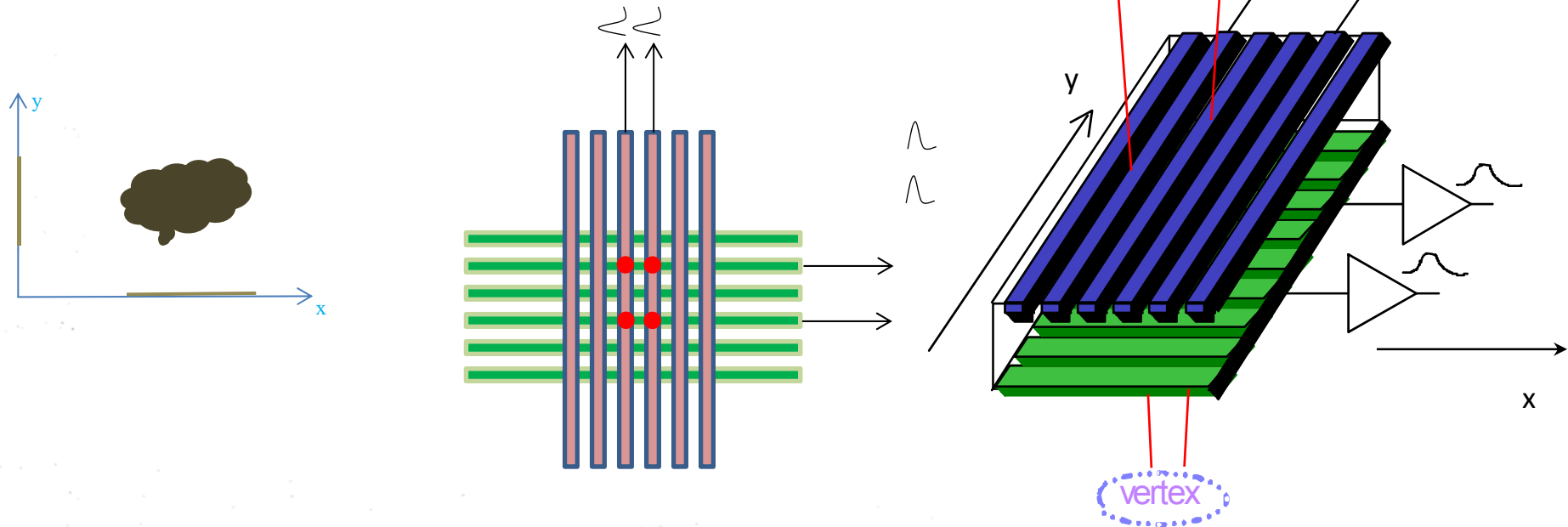
Tests détecteurs



Tests modules

Pourquoi le développement des détecteurs pixels ?

- **Micro-bandes** (double faces)

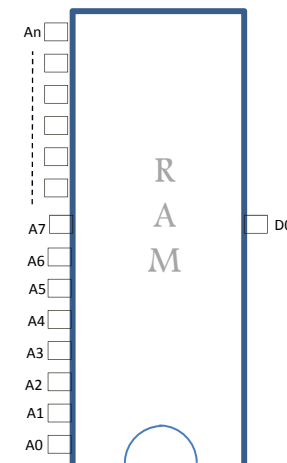


The silicon micropattern detector : a dream ?

(1987)

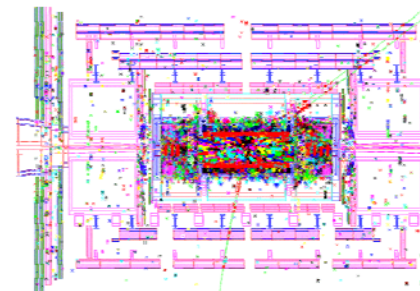
ABSTRACT

The present use of silicon microstrip detectors in elementary particle physics experiments is described and future needs are evaluated. Possibilities and problems to be encountered in the development of a true two-dimensional detector with intelligent data collection are discussed. This paper serves as an introduction to various other contributions to the conference proceedings, either dealing with futuristic device designs or with cautious steps on the road of technology development.



Principe ITK

high pT

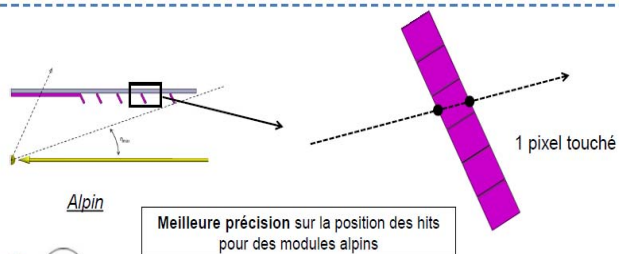
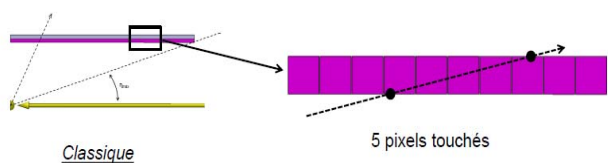
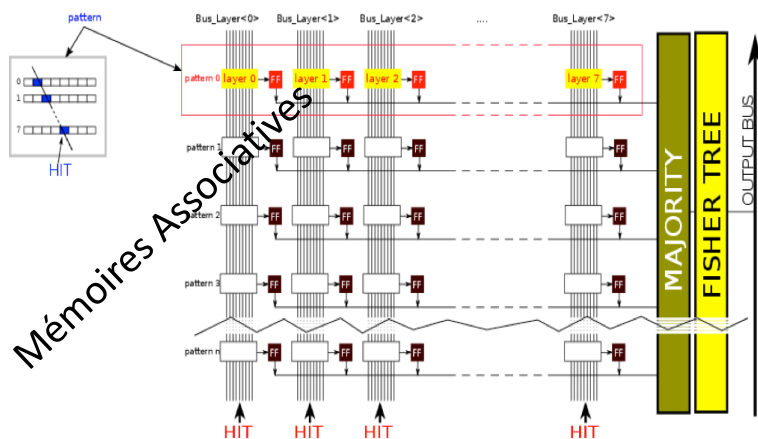
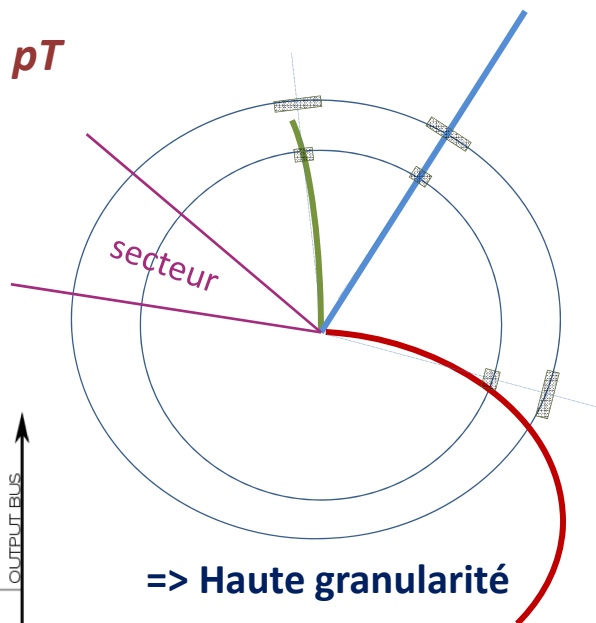


H -> ZZ -> 2e + 2μ

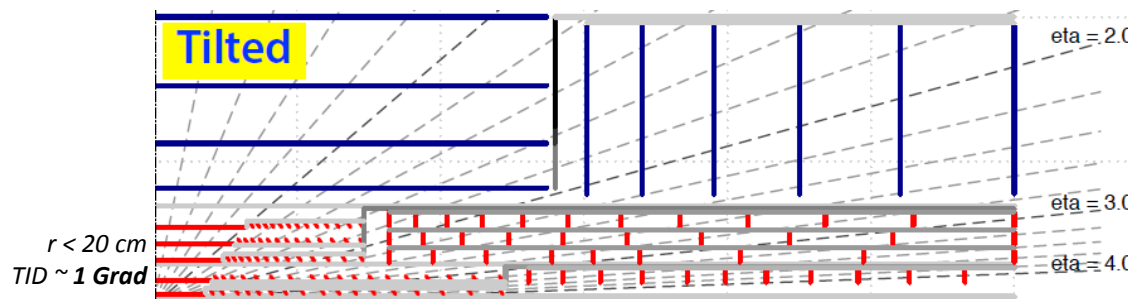
\vec{B}
3.8 T

L1:

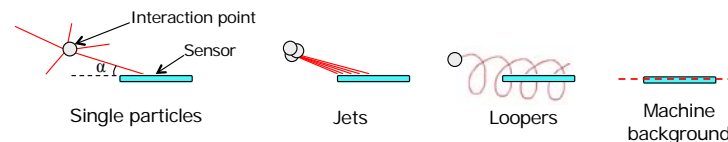
Inner tracker (SCT ; micro-pistes)
Calorimeter
Muon detector



Strip module



5 couches de pixels



Le trigger

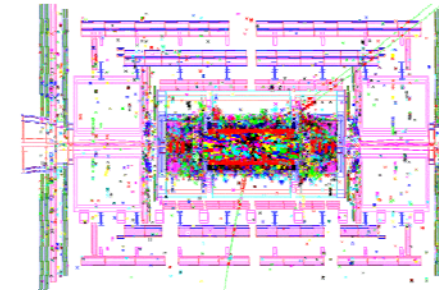
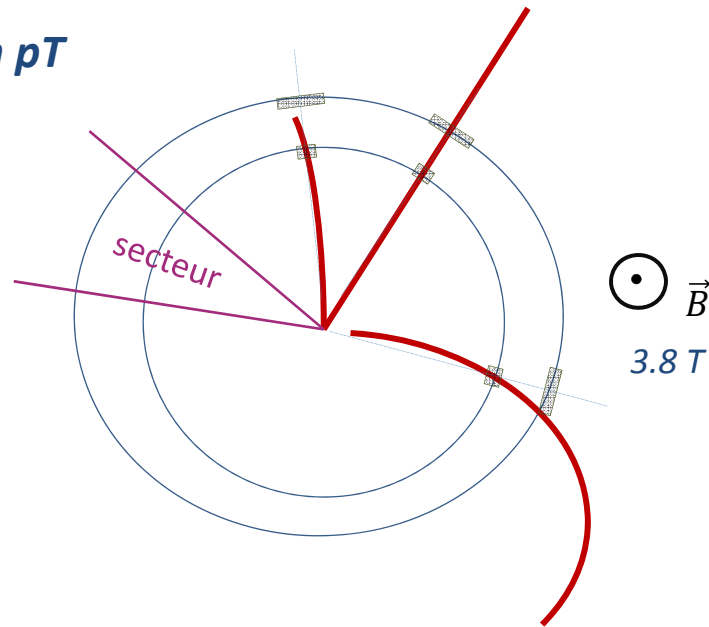
L1
1MHz (100 kHz actuellement)

Latence ~ 10 μ s
(3 μ s actuellement)

L2 (including tracking)
400 kHz (10 kHz actuellement)

Latence ~ 30–60 μ s

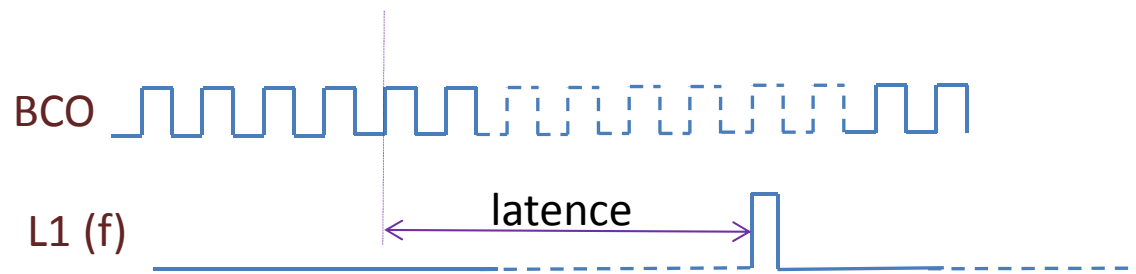
high p_T



H \rightarrow ZZ \rightarrow 2e + 2 μ

L1 :

Inner tracker (SCT)
Calorimeter
Muon detector



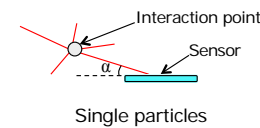
Nbe de période
10 μ s / 25ns
400

(Centroid position encoding)

Région touchée

up link

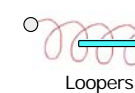
L1



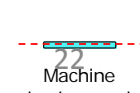
Single particles



Jets



Loopers

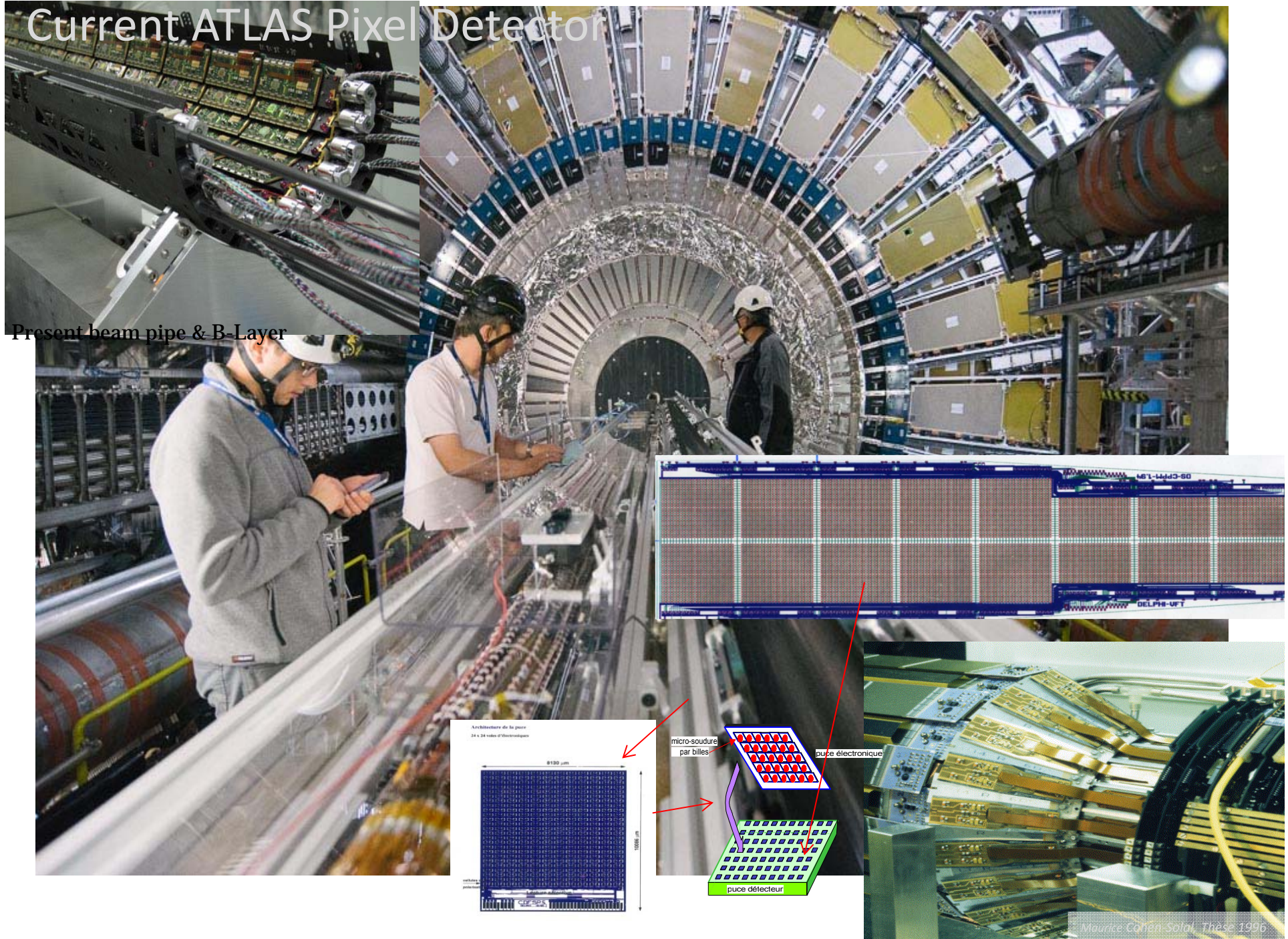


Machine background

[Marconi et al., J. Instrum., 2014]

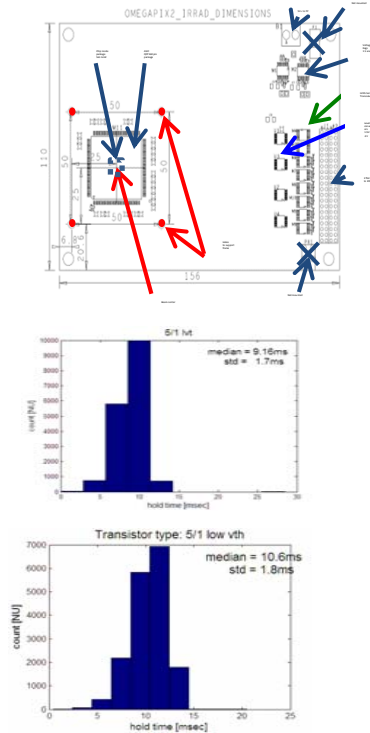
Current ATLAS Pixel Detector

Present beam pipe & B-Layer



Proton Facility, PS East Hall (building 157)

Test of the analog pipeline memory



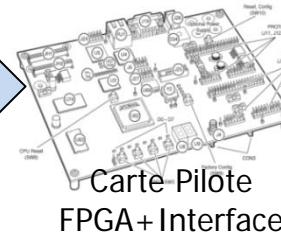
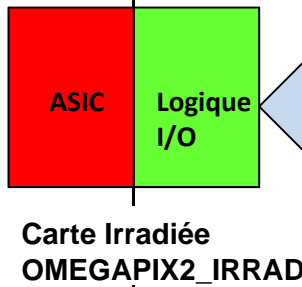
ZONE 2 (IRRAD 9)

ZONE 4

SALLE DE CONTRÔLE



Zone moins exposée



ETHERNET

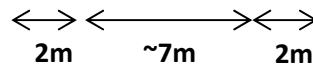
~10 m



PC de monitoring
Soft Labview ou Appli (Labview Application Builder)

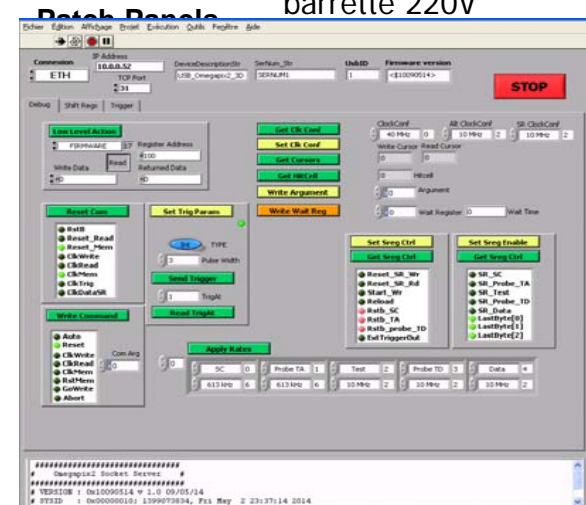
- ~30 I/O + Alim
- 2 câbles plats => IRRAD 9
- 1 câble Alim LV
- 1 barette 220V CH
- 1 câble Ethernet

Possibilité d'éteindre et allumer la barrette 220V



Irradiation @ CERN (24 GeV p)
Integrated Fluence $3.5 \cdot 10^{15}$ p/cm²

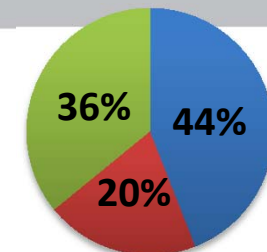
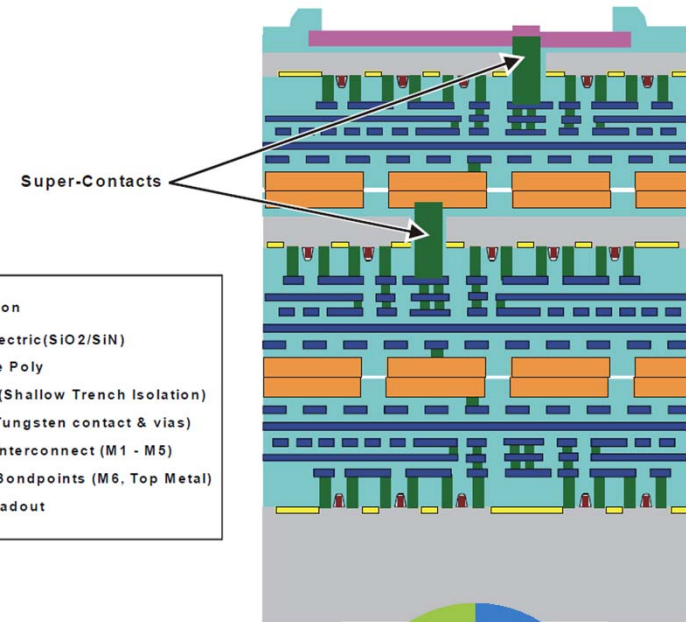
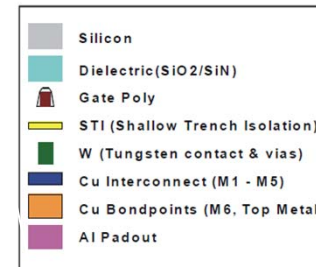
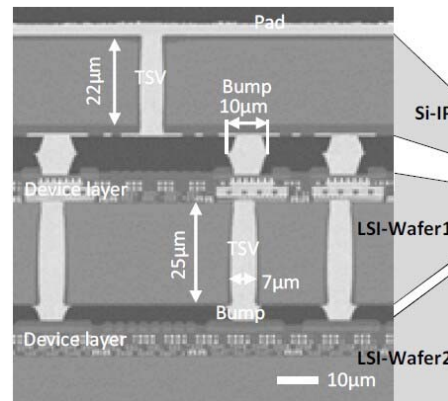
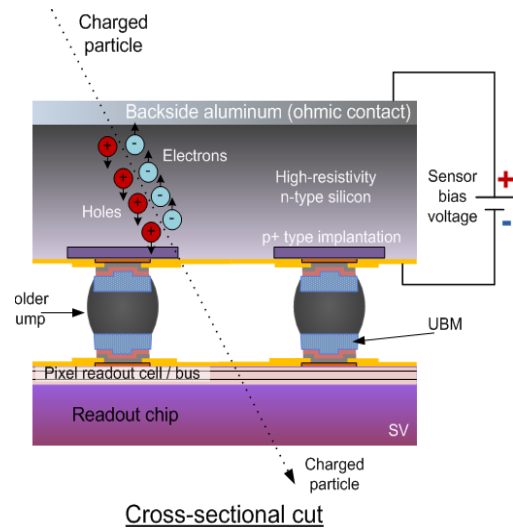
run mai 2015



Pixel sensor(s) *not yet determined* Innovation dans les Interconnexions des modules

Module ~ 170 SFr/cm²

Problématique : Réduction du coût total système des pixels (~ 32 MSFr) dont (18MSFr) Modules hybrides



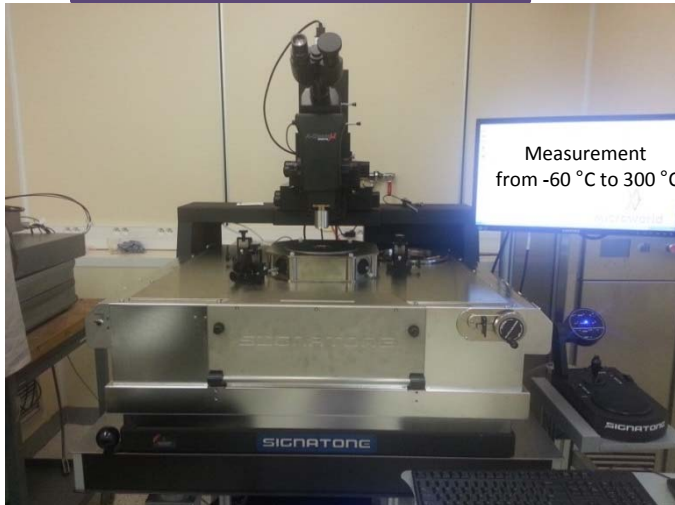
■ Interconnect ■ FE Chips ■ Sensors

Objectif : réduire le coût de 40%

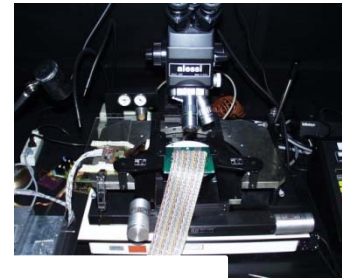
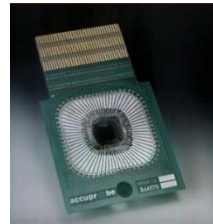
Sigmatone

New 50 m2 cleanroom with acquisition of semi-automatic testing system machine.
For medium or large scale testing, such as for the HL-LHC.

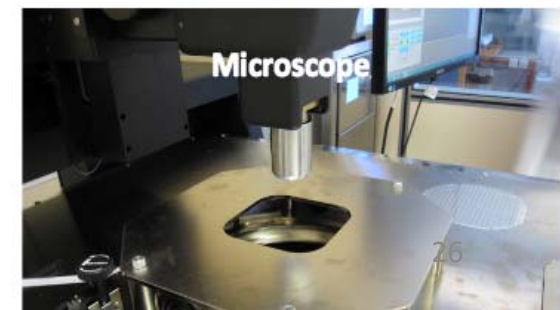
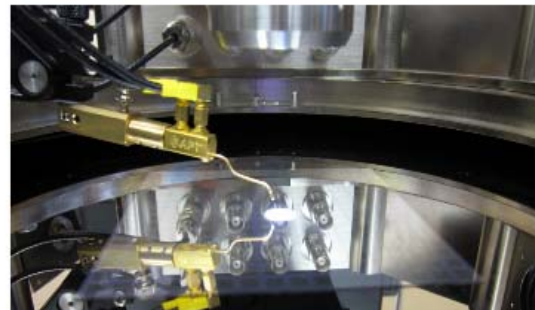
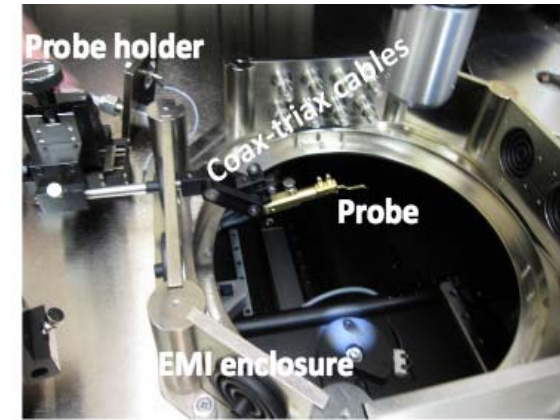
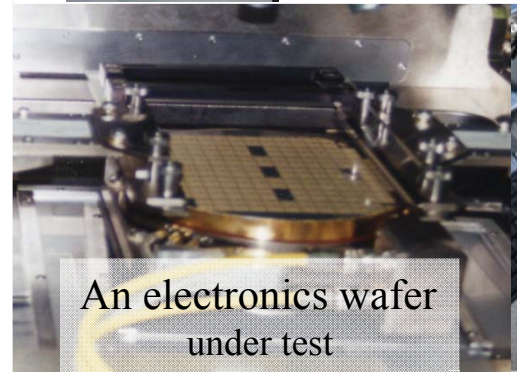
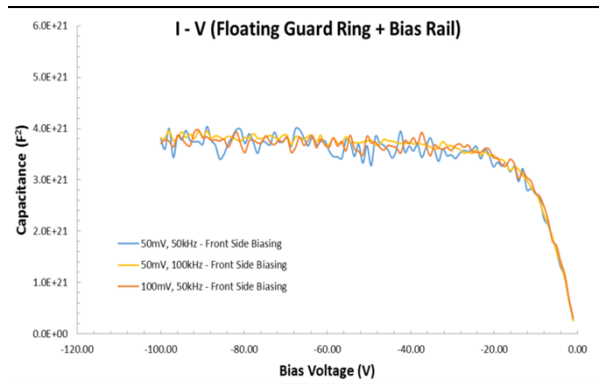
SEMI AUTOMATIC PROBE STATION



Measurement from -60 °C to 300 °C



Test de semi conducteur



Test, caractérisation & appariement

Technologies



Omegapix_1 **130 nm Chartered Semiconductor**

64 x 24 pixels, pas : 50µm x 50 µm

Omegapix_2 (3D) **130 nm Global Foundries**

96 x 24 pixels, pas : 35µm x 200 µm

FE-I3 (2003) **250 nm IBM**

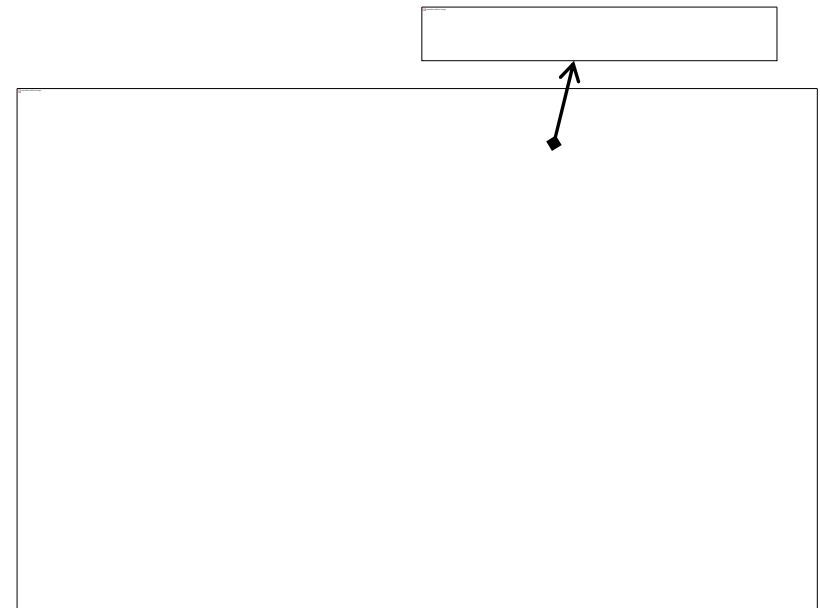
18 x 160 pixels, pas : 50µm x 400 µm

FE-I4-B (2011) **130 nm IBM**

80 x 336 pixels, pas : 50µm x 250 µm

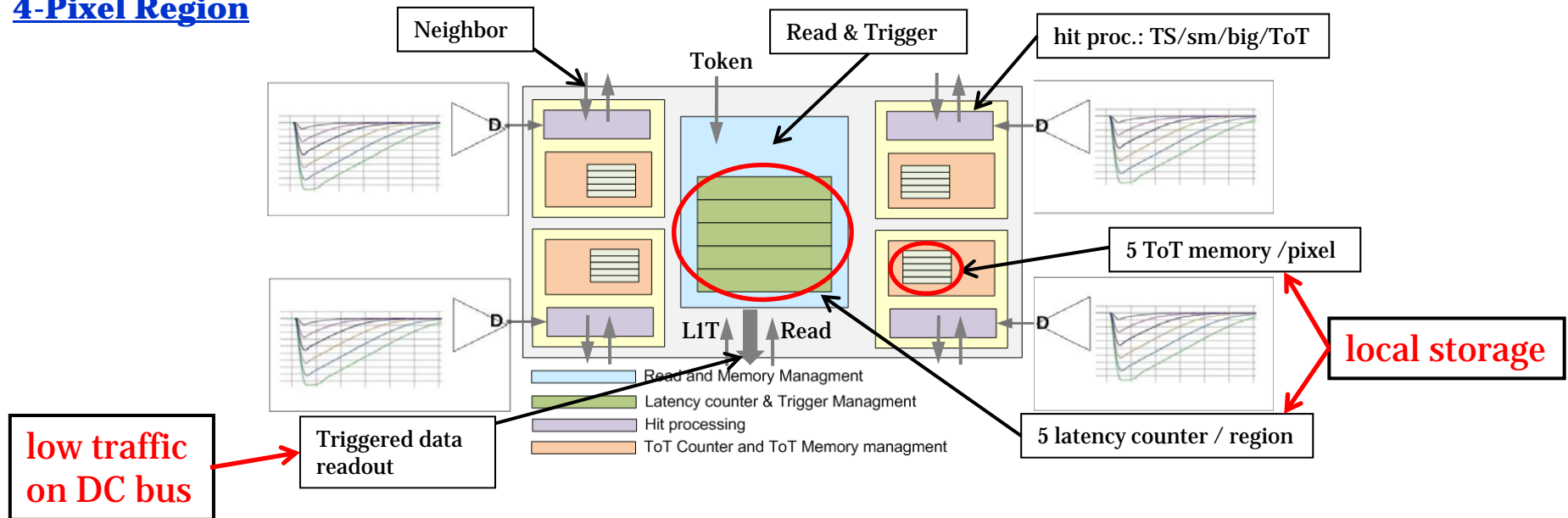
RD53-A (2016) **65 nm TSMC**

400 x 200 pixels pas : 50µm x 50 µm



Digital Pixel: Regional Architecture

4-Pixel Region

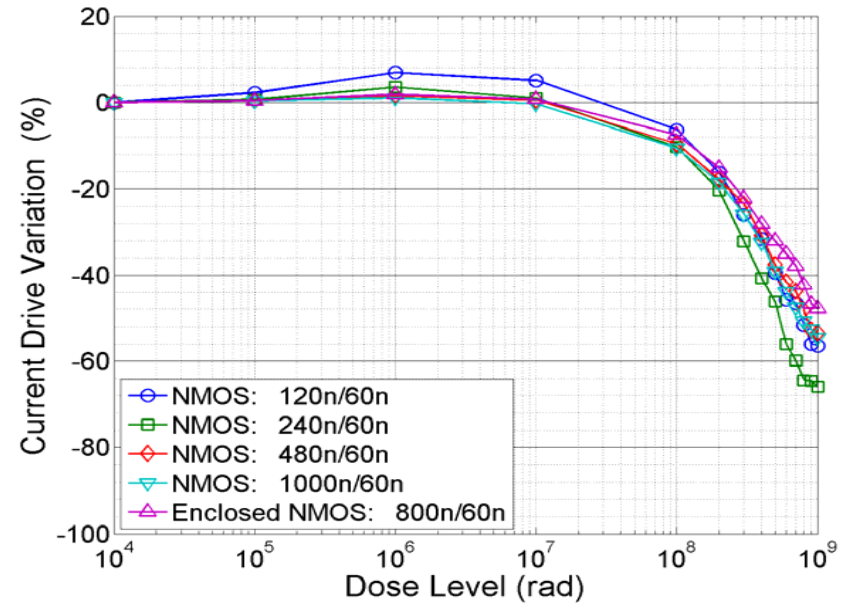
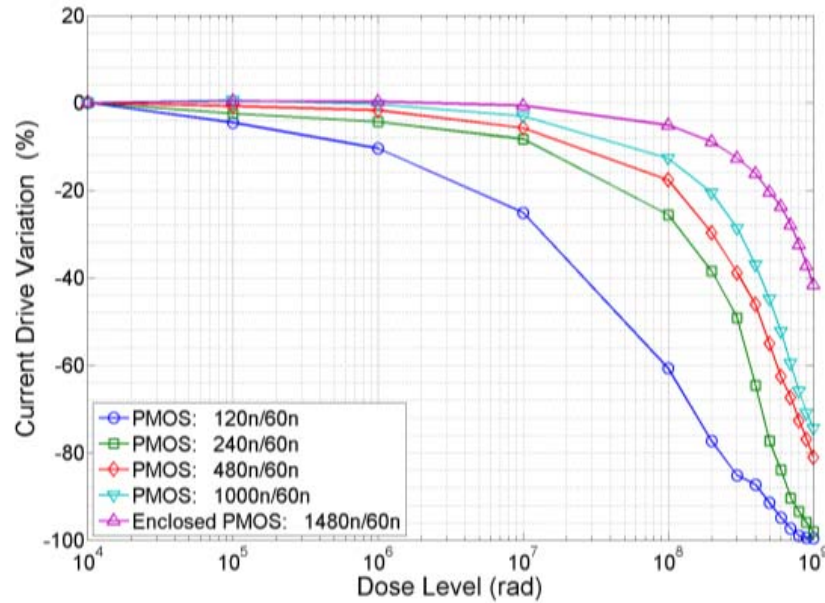


- Store hits locally in region until LIT.
- Only 0.25% of pixel hits are shipped to EoC → DC bus traffic “low”.
- Each pixel is tied to its neighbors -time info- (clustered nature of real hits). Small hits are close to large hits! To record small hits, use position instead of time. Handle on TW.

Summary:

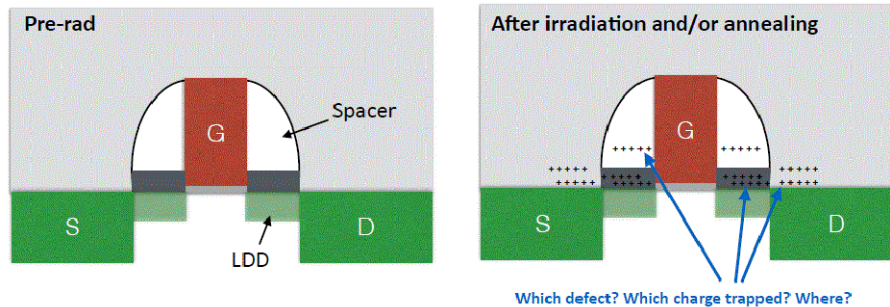
- Physics simulation → Efficient architecture.
- Spatial association of digital hit to recover lower analog performance.
- Shared resources & hit not moved around → Lowers digital power consumption.

WG1 : Radiation



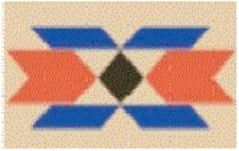
Recommandations analog block :

- PMOS $W \geq 300\text{nm}$, $L \geq 120\text{nm}$; NMOS $L \geq 120\text{nm}$ → puissance, surface, performance
- Travail présent : **Modélisation** (extraction de paramètres "Radiation corner").

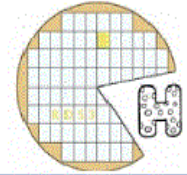


TRL with delays

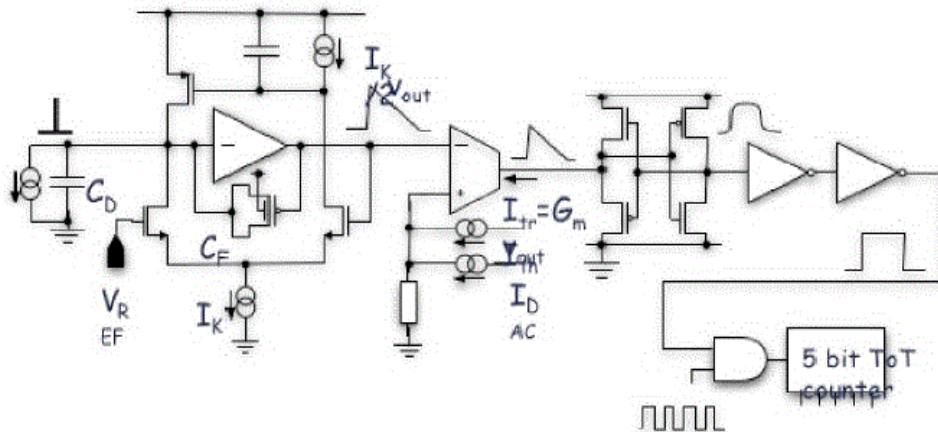
SEU	area	Error rate		
		Number of errors/spill		
		0 to 1	1 to 0	All
DFF for shift register	14.4 μm^2	5.6	2.9	4.2
TRL for configuration	40 μm^2	0.082	0.04	0.06
TRL + delay	54 μm^2	0.064	0.015	0.04



WG5 : Analog Front-End Design

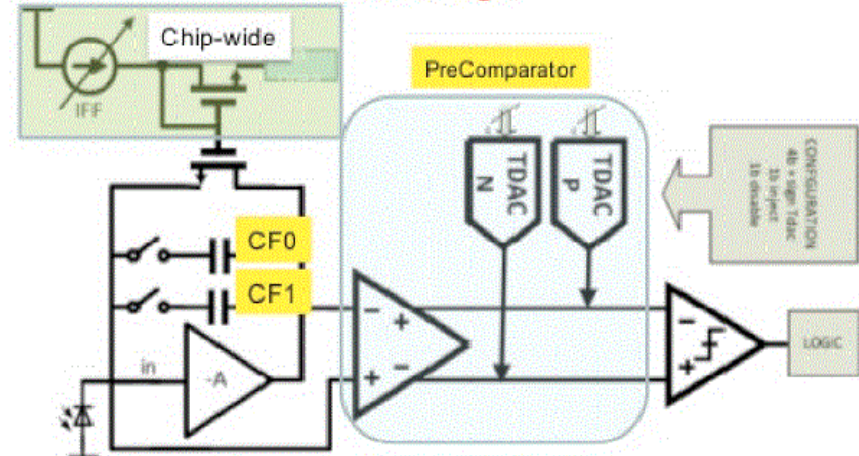


INFN-Pavia design



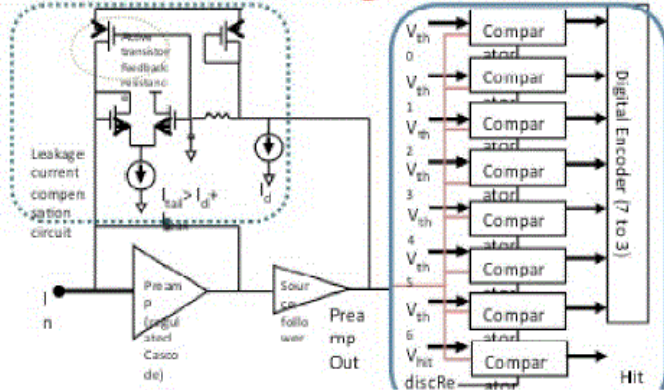
Single stage with current comparator and ToT counter

LBL design



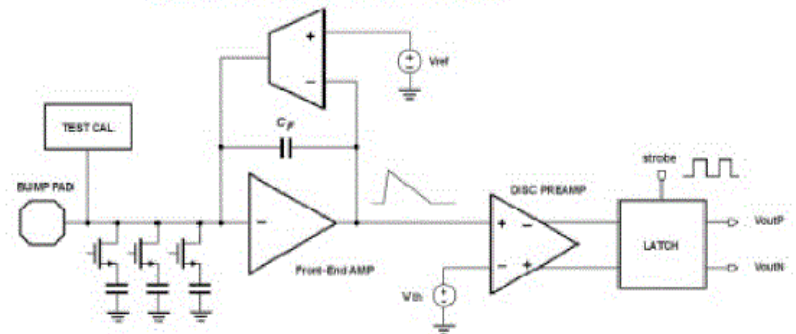
1 of 4 in quad "analog island" of FE65_P2

FNAL design



Synchronous: resets every bunch crossing. Flash ADC

INFN-Torino design



Single stage with SAR-like ToT counter using synchronous comparator

Block IP : WG 6

ADCs, DACs, sensors (temp, current, radiation), Bandgap references, analog buffers, specialized storage cells, PLL, programmable delay, serializer, differential inputs/outputs, shunt-LDO, etc.

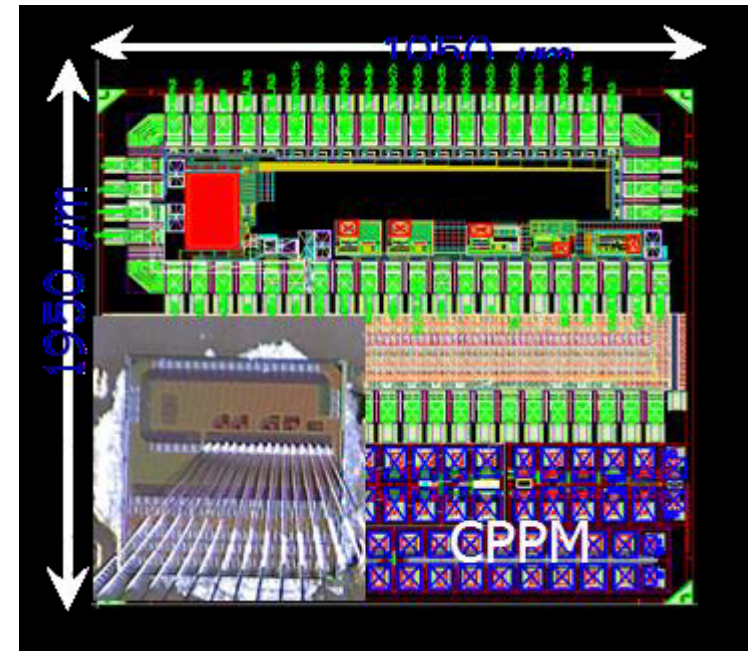
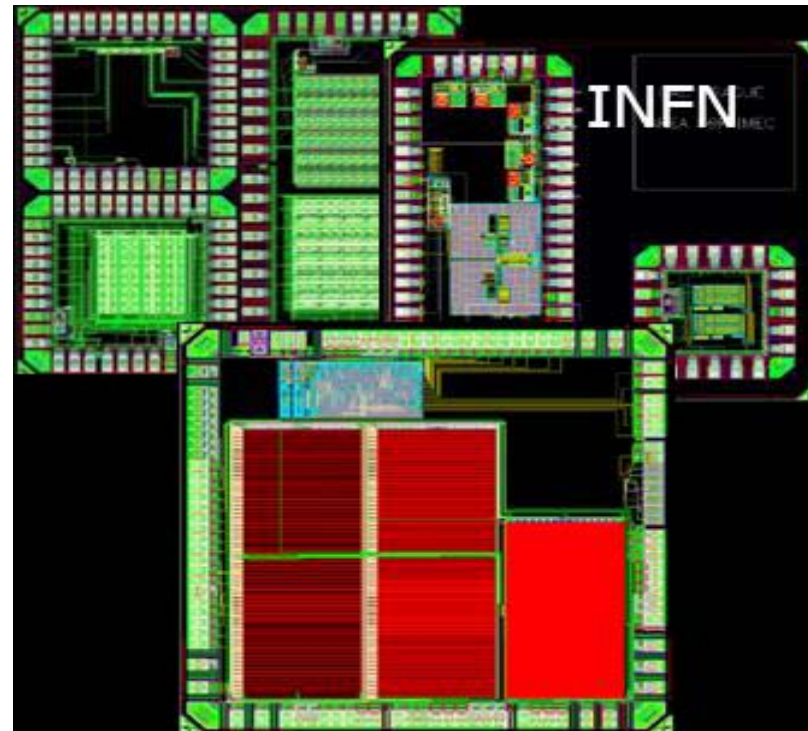
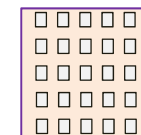
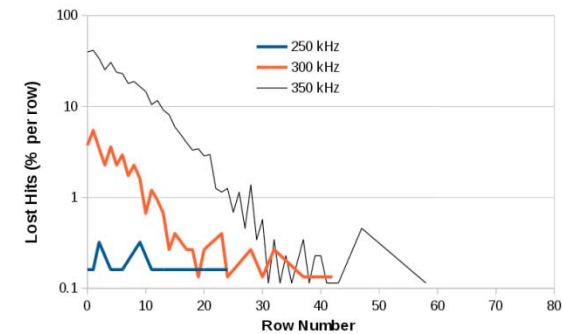
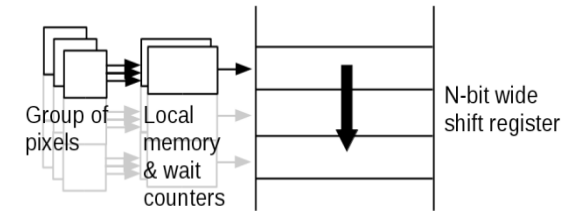
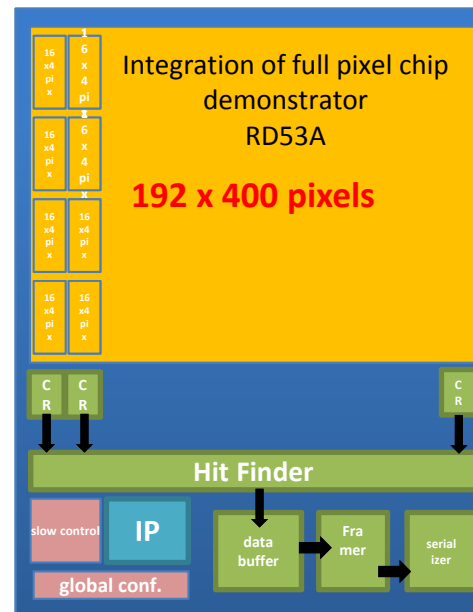


Schéma band gap

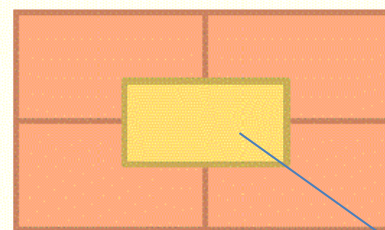
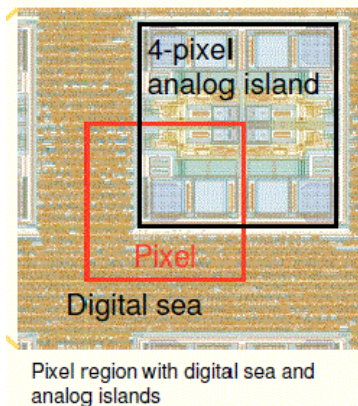


Top Level Integration (WG2)

Specification	Value	Comment or Test Conditions
Input polarity	Negative	
Interior pixel capacitance	< 100 fF	this applies to most pixels
Edge pixel capacitance	< 200 fF	see subsection on edge pixels
Interior pixel leakage current	< 10 nA	
Edge* pixel leakage current	< 20 nA	*see Sec. 5.2 for details
Min. stable threshold setting	600 e ⁻	With 50 fF load, 4 μA/pixel analog. For free running discriminated pixel. See Sec. 3.1
Min. charge above threshold resulting in < 25 ns time walk	600 e ⁻	With 50 fF load, 4 μA/pixel analog. For free running discriminated pixel. See Sec. 3.1
Min. in-time threshold with free-running front end	1200 e ⁻	With 50 fF load, 4 μA/pixel analog. Simply the sum of the two above lines
Min. in-time threshold if using synchronous reset	750 e ⁻	With 50 fF load, 4 μA/pixel analog. See Sec. 3.1
Hit loss from in-pixel pileup	≤ 1%	at 75 kHz avg. hit rate. See Sec. 3.2
Recovery from saturation	< 1 μs	See Sec. 3.2 for discussion
Trigger rate	1 MHz	
Trigger latency	12.5 μs	
Noise occupancy per pixel	< 10 ⁻⁶	50 fF load; in a 25 ns interval
Single pixel noise (ENC)	design-dependent	See Sec. 3.1
Radiation dose	500 Mrad	delivered at -15°C. Room T annealing only
Temperature range	-40°C to +40°C	
Current consumption, analog	4 μA/pixel	periphery consumption not included
Current consumption, digital	< 4 μA/pixel	periphery consumption not included
Current consumption, Total	< 500 mA/cm ²	Note this is 1 W/cm ² at 2 V input
SEU upset rate, full chip	< 0.05/hr	in 1.5 GHz/cm ² particle flux
SEU upset rate affecting single pixel configuration	< 100/hr	in 1.5 GHz/cm ² particle flux



RD53-A



50 x 250 μm²
130 nm
Type FEI-4

Digital
analog

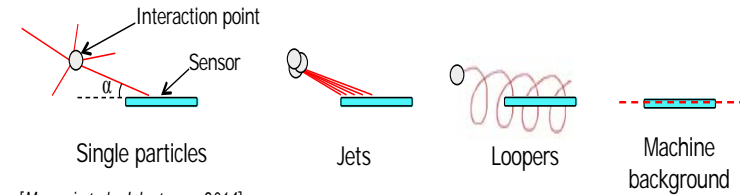
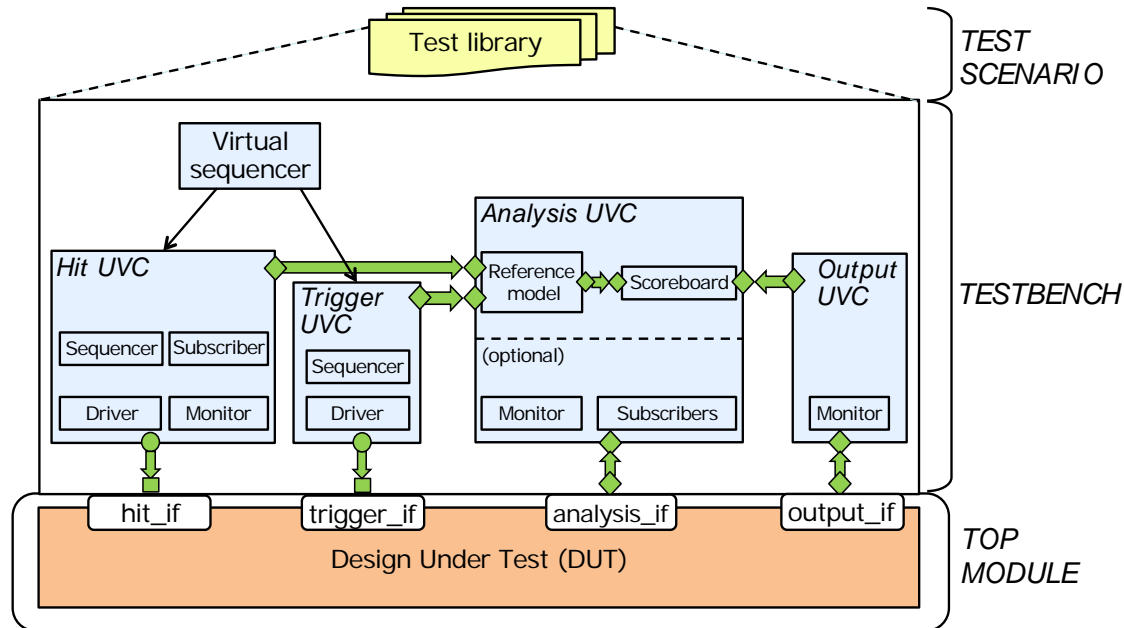
50 x 50 μm²
65 nm
Type RD53

WG3 : Modélisation & Simulations

VEPIX53: Verification Environment for RD53 PIXel chips

(SystemVerilog/**U.V.M.**, available: git.cern.ch/reps/VEPIX53)

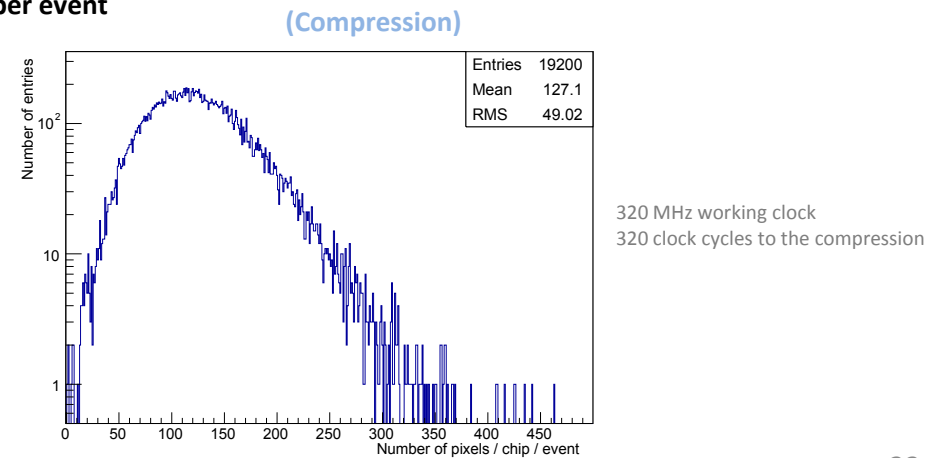
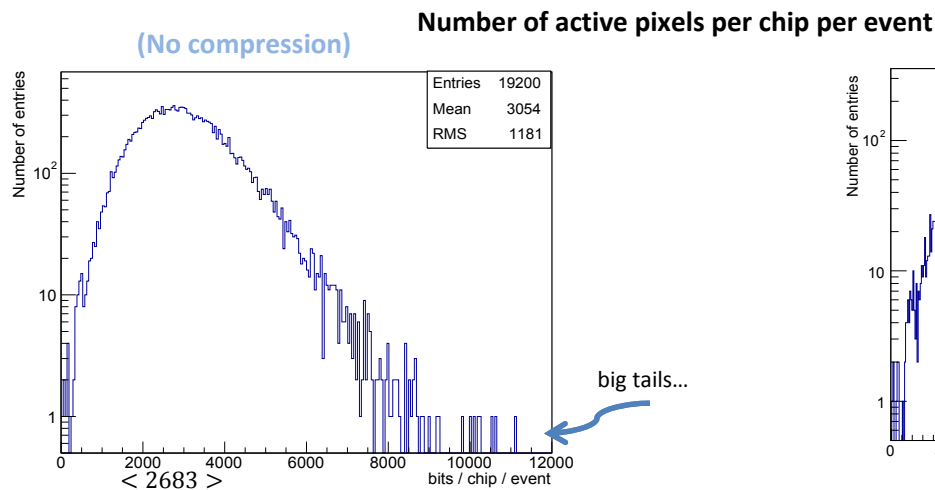
verifications



- hit generation and injection
- monitoring of pixel chip input and output
- conformity checks and statistics collection
- S.E.U.

Hit : ~ 2 GHz/cm²

Readout rate (~ 4.8 Gbits/s per chip for 1MHz L1 trigger rate)



I/O :WG 4 (Roberto Beccherle)

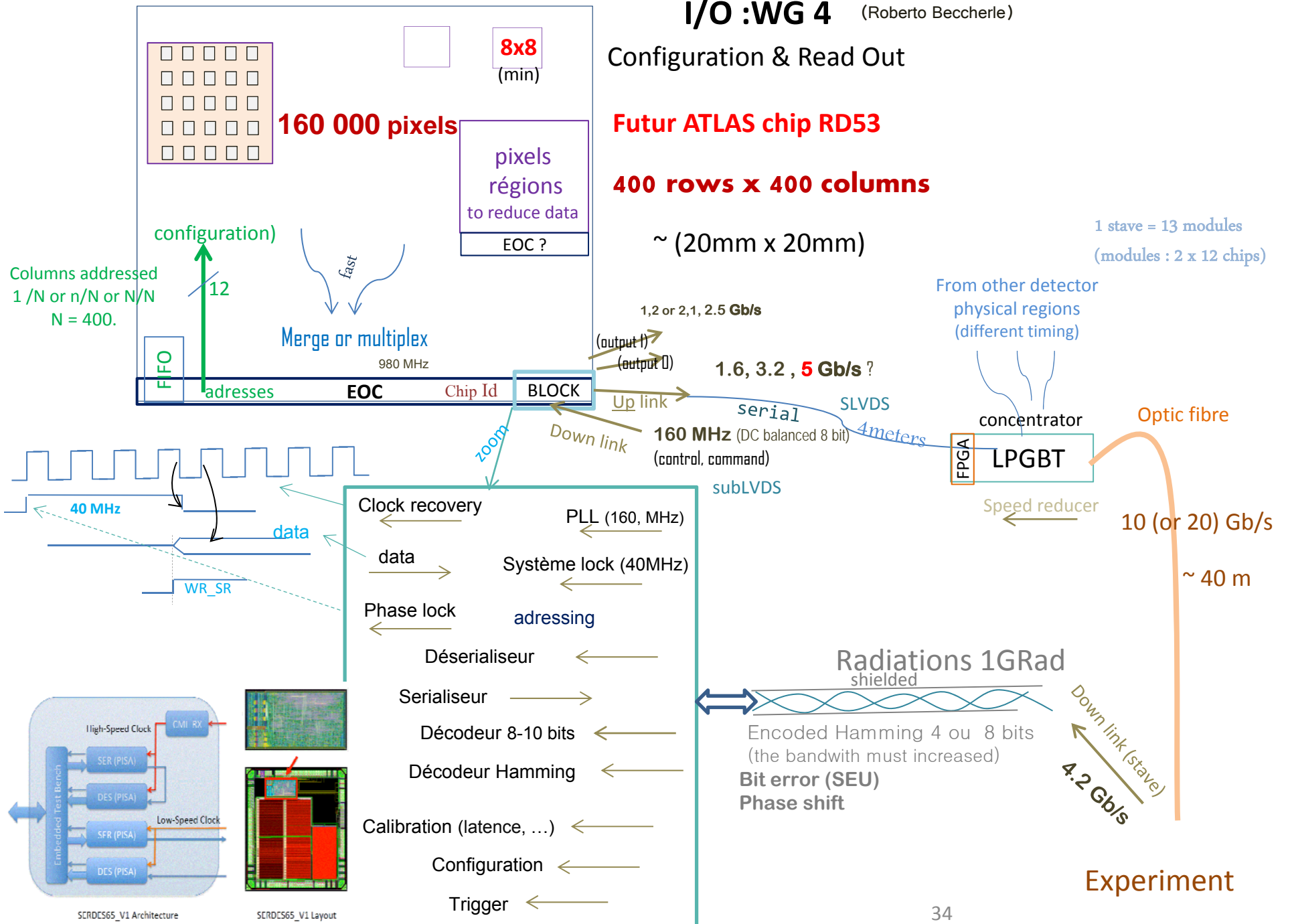
Configuration & Read Out

Futur ATLAS chip RD53

400 rows x 400 columns

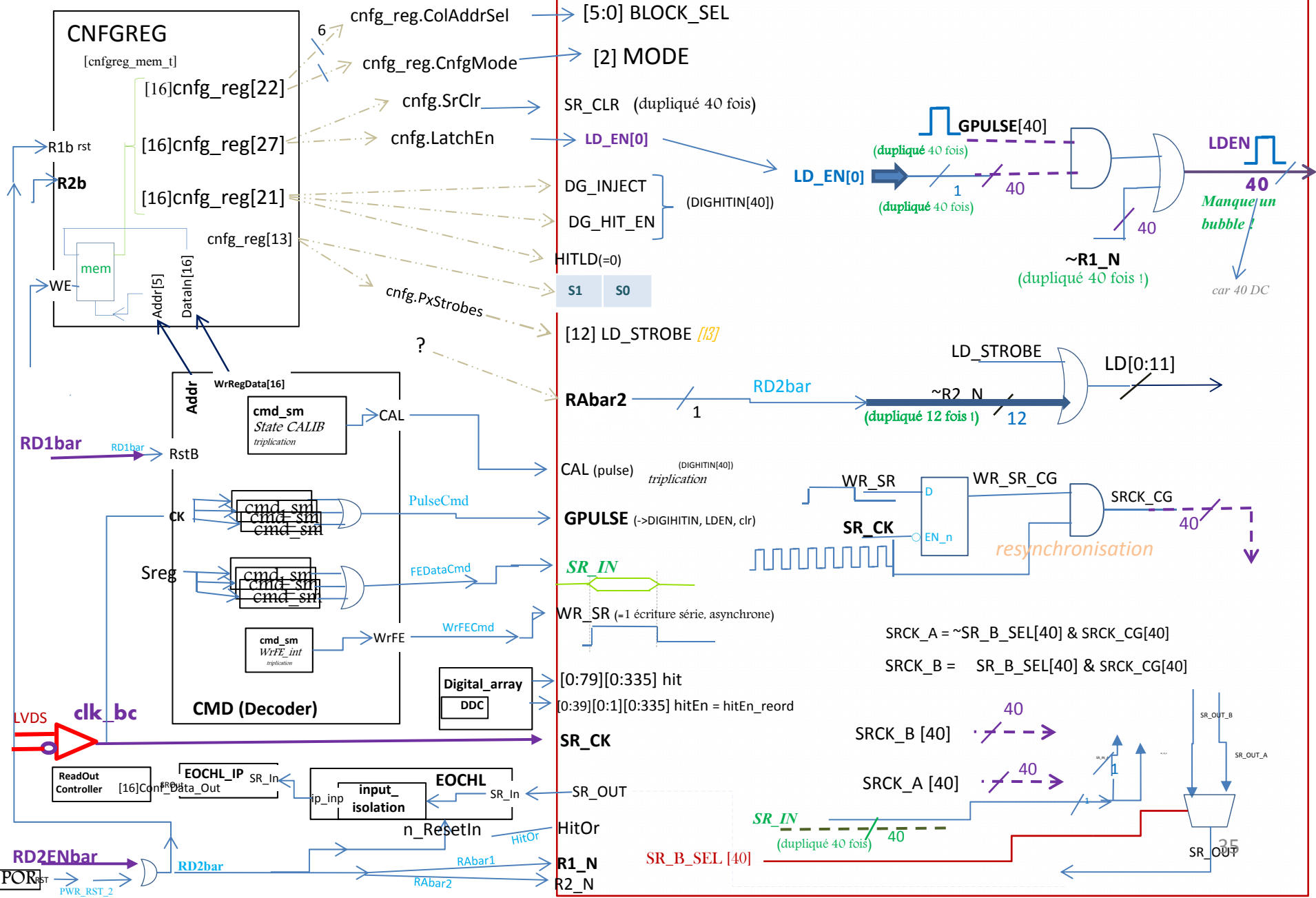
~ (20mm x 20mm)

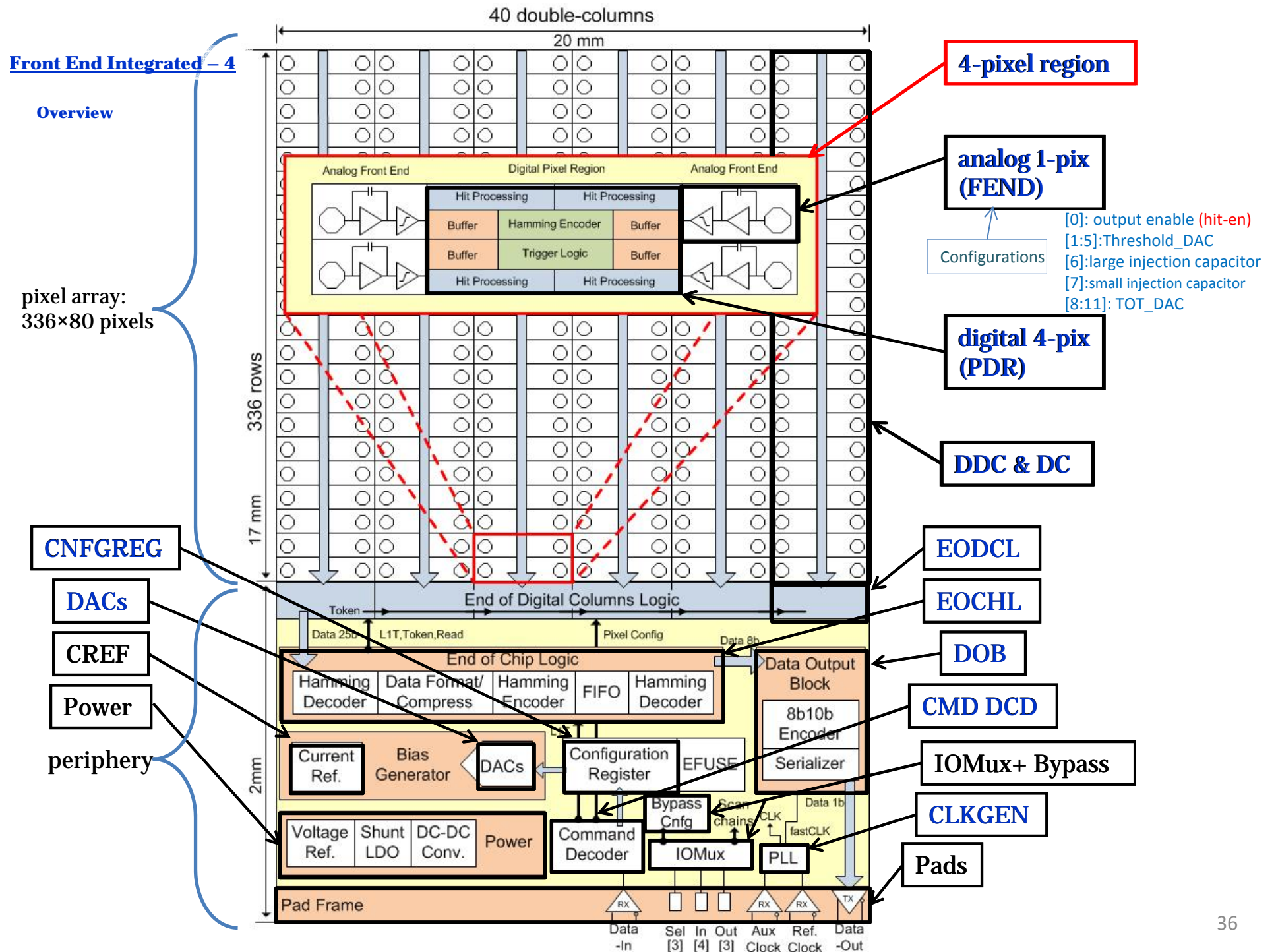
1 stave = 13 modules
(modules : 2 x 12 chips)



I/O interface

(PDR+DDC+EODCL+DOB+EOCHL+CNFGREG)





message pas clair > configurer)
nombreux warning à la synthèse (reprendre le code Verilog, options de compilation)

RTL Compiler Flow Wizard (organisation, les techfiles, corner, ...)
Problème de version 11.1 et 14.1

Erreur : cellule d'ajustement fit pas sur les sites technologiques !

Vérification Etapes EDI
floating gate (D & S)
Slack hold time Incisive 12.10

Simulation AMS ! Double panneau !

A.R.10.A.R.10.rep*
A.R.11.A.R.13.AP.rep*
A.R.1.POLY.rep*
A.R.2.POLY.rep*
A.R.3.CO.rep*
A.R.4.A.R.7.VIA1.rep*
A.R.4.VIA2.rep*
A.R.4.VIA3.rep*
A.R.4.VIA4.rep*
A.R.4.VIA5.rep*
A.R.4.VIA6.rep*
A.R.4.VIA7.rep*
A.R.4.VIA8.rep*
A.R.6.A.R.8.M1.rep*
A.R.6.A.R.8.M2.rep*
A.R.6.A.R.8.M3.rep*
A.R.6.A.R.8.M5.rep*
A.R.6.A.R.8.M6.rep*
A.R.6.A.R.8.M7.rep*
A.R.6.A.R.8.M8.rep*
A.R.6.M9.rep*
A.R.7.VIA2.rep*
A.R.7.VIA3.rep*
A.R.MIM.3.AP.CBM.rep*
A.R.MIM.3.AP.CTM.rep*
A.R.MIM.3.M8.CBM.rep*
A.R.MIM.3.M8.CTM.rep*
A.R.MIM.3.M9.CTM.rep*
A.R.MIM.3.M9.CTM.rep*
A.R.MIM.4.RV.CBM.rep*
A.R.MIM.4.RV.CTM.rep*
A.R.MIM.4.VIA7.CBM.r
A.R.MIM.4.VIA7.CTM.r
A.R.MIM.4.VIA8.CBM.r
A.R.MIM.4.VIA8.CTM.r

DNR.R.7.rep*
DRC_CONF_COLUMN_CHIP_20160331_1326.gz_WD.gds.gds
DRC_CONF_COLUMN_CHIP_20160331_1326.gz_WD.gds.log
DRC_CONF_COLUMN_CHIP_20160331_1326.gz_WD.gds.sum
DRC_CONF_COLUMN_CHIP_20160331_1326.gz_WD.gds.txt*
DRC_CONF_COLUMN_CHIP_20160331_1326.gz_WD.gds.tar.gz*
DRC_CONF_COLUMN_CHIP_20160331_1326.gz_WD.gds.txt*
ESD.1g.NMOS.rep*
ESD.17g.PMOS.rep*
ESD.1g.hv_n.rep*
ESD.1g.hv_p.rep*
IND.DN.1H.M1.density*
IND.DN.1H.M2.density*
IND.DN.1H.M3.density*
IND.DN.1H.M4.density*
IND.DN.1H.M5.density*
IND.DN.1H.M6.density*
IND.DN.1H.M7.density*
IND.DN.1H.M8.density*
IND.DN.1H.M9.density*
IND.DN.1L.M1.density*
IND.DN.1L.M2.density*
IND.DN.1L.M3.density*
IND.DN.1L.M4.density*
IND.DN.1L.M5.density*
IND.DN.1L.M6.density*
IND.DN.1L.M7.density*
IND.DN.1L.M8.density*
IND.DN.1L.M9.density*
IND.DN.6.density*
IND_MD.DN.11L.M
IND_MD.DN.6.den
IND_MD.DN.7.M1.
IND_MD.DN.7.M2.
IND_MD.DN.7.M3.
IND_MD.DN.7.M4.
IND_MD.DN.7.M5.
IND_MD.DN.7.M6.
IND_MD.DN.7.M7.
IND_MD.DN.7.M8.
IND_MD.DN.8.M2.
IND_MD.DN.8.M3.
IND_MD.DN.8.M4.
IND_MD.DN.8.M5.
IND_MD.DN.8.M6.
IND_MD.DN.8.M7.
IND_MD.DN.8.M8.
IND_MD.DN.9.M1.density*
IND_MD.DN.9.M2.density*
IND_MD.DN.9.M3.density*
IND_MD.DN.9.M4.density*
IND_MD.DN.9.M5.density*
IND_MD.DN.9.M6.density*
IND_MD.DN.9.M7.density*
M2.DN.1.density*
M2.DN.2.density*
M2.DN.4.density*
M2.DN.5.density*
M2.DN.6.M2.density*
M2.DN.6.M3.density*
M2.DN.6.M4.density*
M2.DN.6.M5.density*
M2.DN.6.M6.density*
M4.DN.1.1.density*
M4.DN.1.density*
M4.DN.2.density*
M4.DN.3.density*
M4.DN.3.density*
M4.DN.6.M4.density*
M4.DN.6.M5.density*
M4.DN.6.M6.density*
M5.DN.1.1.density*
M5.DN.2.density*
M5.DN.4.density*

Licences permettant d'utiliser les bibliothèques ARM et TSMC
65nm

ED (faire et refaire; rails d'alim! ; ...)

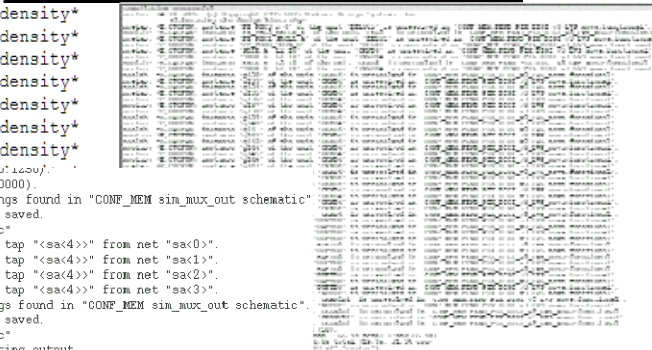
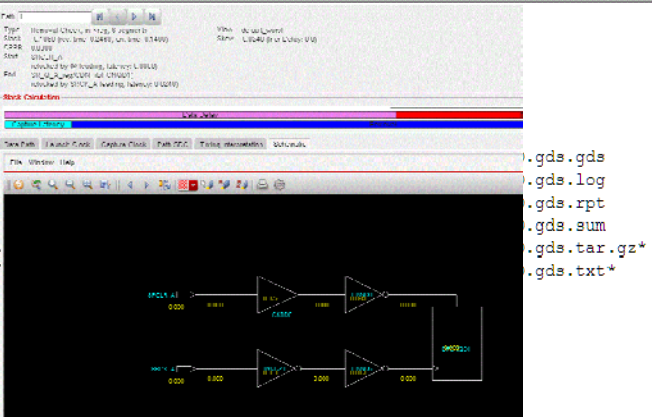
connect rules à éc

Impédance d'entrée
Clock tree

simulation ne se lance pas !
Extraction ecpixl

Sealing ring
Chip Corner Stress Stress Relief Pattern

ftp permission denied
USE PORET or PASV first



ratio.log*
via2_tri_tier_inner_ratio.log*
via2_tri_tier_mid_ratio.log*
via2_tri_tier_outer_ratio.log*
via3_single_ratio.log*
via3_stagger_inner_ratio.log*
via3_stagger_outer_ratio.log*
via3_tri_tier_inner_ratio.log*
via3_tri_tier_mid_ratio.log*
via3_tri_tier_outer_ratio.log*
via4_single_ratio.log*
via4_stagger_inner_ratio.log*
via4_stagger_outer_ratio.log*
via4_tri_tier_inner_ratio.log*
via4_tri_tier_mid_ratio.log*
via4_tri_tier_outer_ratio.log*
via5_single_ratio.log*
via5_stagger_inner_ratio.log*
via5_stagger_outer_ratio.log*
via5_tri_tier_inner_ratio.log*
via5_tri_tier_mid_ratio.log*
via5_tri_tier_outer_ratio.log*
via6_single_ratio.log*
via6_stagger_inner_ratio.log*
via6_stagger_outer_ratio.log*
via6_tri_tier_inner_ratio.log*
via6_tri_tier_mid_ratio.log*
via6_tri_tier_outer_ratio.log*
Texte RVE Calibre GDS

Data base results from IMC

Compétences outils



DIGITAL

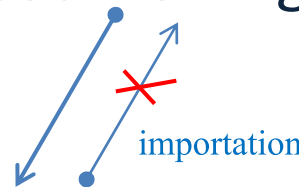
Comportemental
Simulation
Synthèse
Layout

Verilog System
Incisive 12.1
RTL Compiler 12.1
Encounter Digital Implementation 14.1
(clock tree generation)

ANALOGIQUE

Analogique
Simulation
Verification

Virtuoso
Spectre & **AMS**
Calibre



« ANALOG ON TOP »

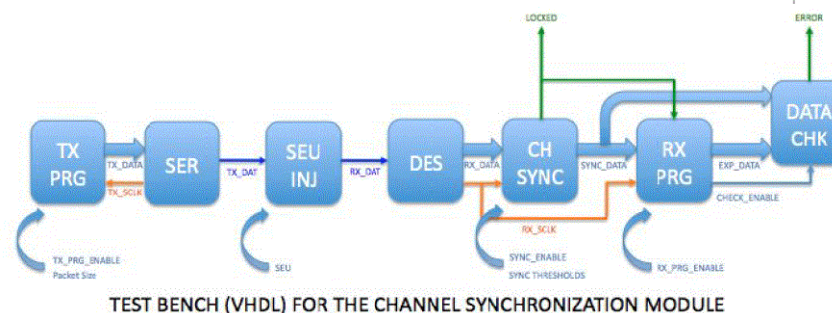
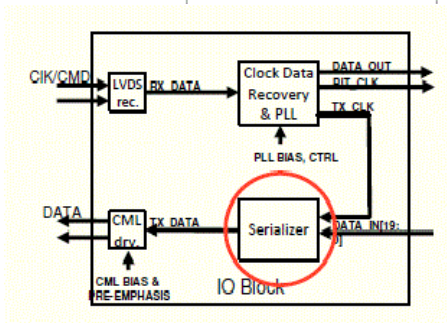
(Assemblage , vérification, simulation post layout)

IO WG

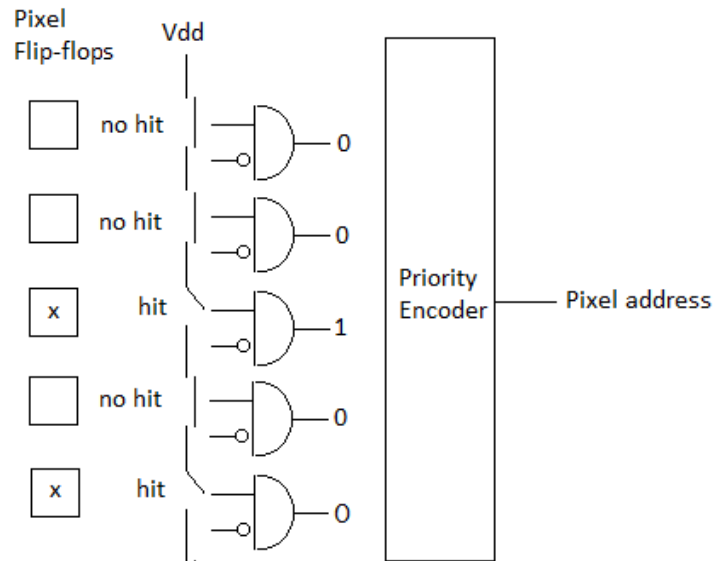
In order to work on the RD53-A chip, have to be implemented.

- PLL, SerDes, Clk alignment, ...
- Command Decoder, Configuration Memory, event builder, data compression, ...

Group	Area of Interest	Foreseen manpower (over 6 months)
Bonn	CDR, PLL, SER, CML TX	0.9
Torino	PLL	0.4
Pisa	Command Decoder, SerDes, Channel Synchronization, SLVS Driver-Receiver	1.3
LBNL	5Gbps output, data compression	0.2
LPNHE	EoC Data Path	0.5
		3.3



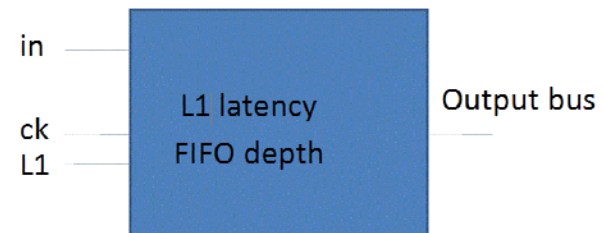
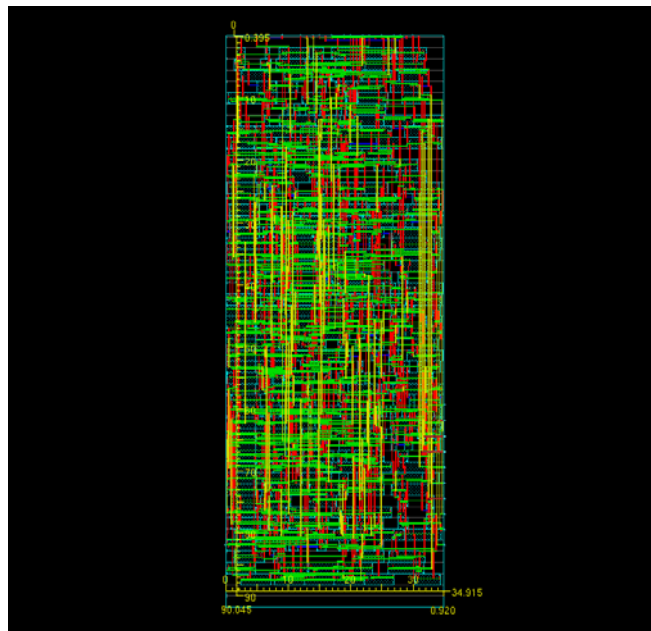
Proposal ...



sparse scan readout

Extract a stack of addresses of pixels hit in time with L1

Building block



- VHDL model
- Cells library
- I/O locations file (x,y in microns)
- Dimensions (FIFO depth 16)

OK
65nm TSMC
text file
35 x 70 μm^2

FIFO depth 24

35 x 90 mm²

AIDA

European project

Advanced European Infrastructures for
Detectors at Accelerators



**TecHnology
Innovations for
INtelligent
Trackers**

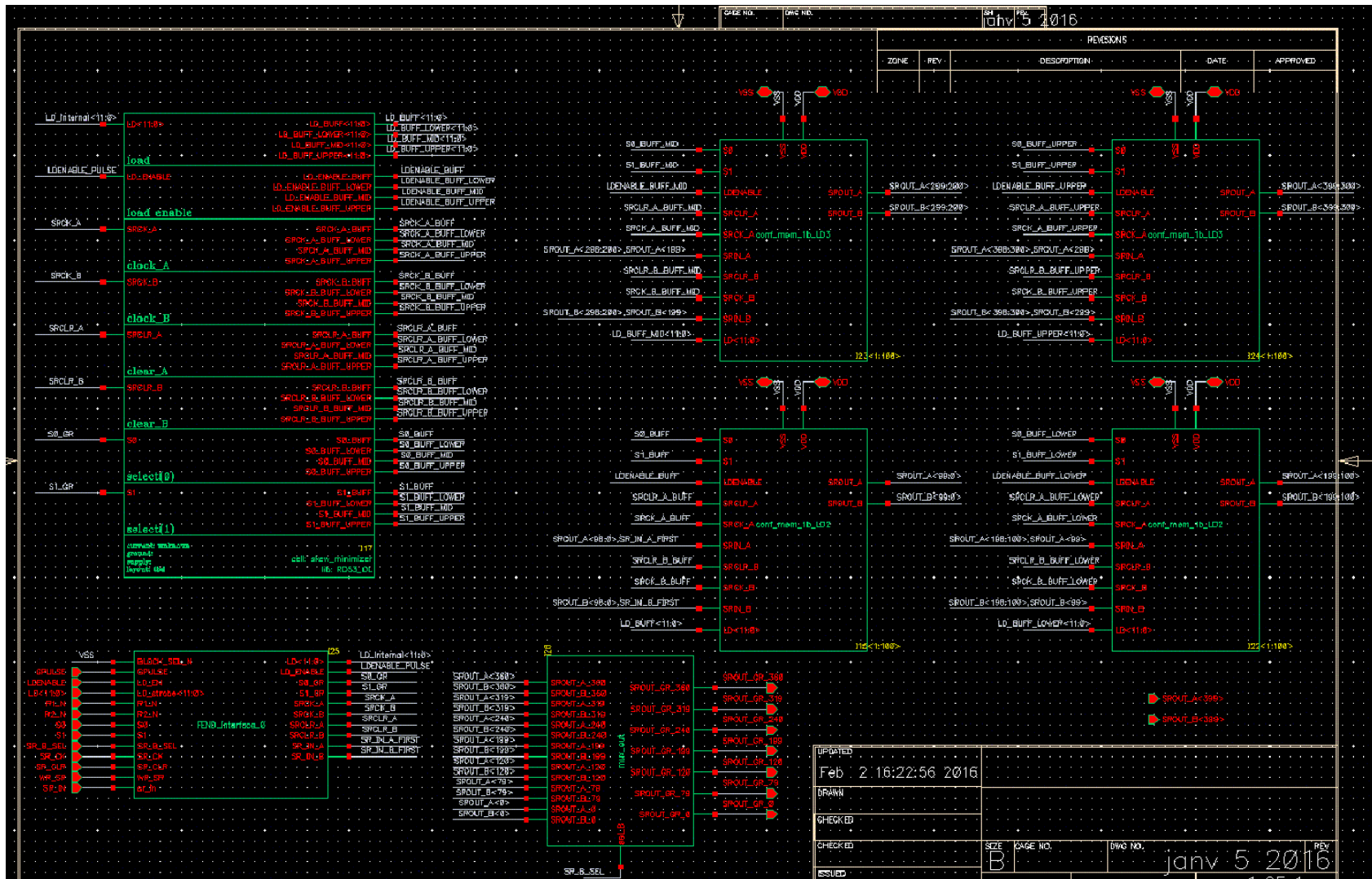
Projet phare p2io
(Labex retenus pour 2ème
lecture)

Schematic « top level »

Final integration : Conf Column Chip ; C3

- « Génération automatique »
- Dimensions ~ 1.0 mm x 1.0 mm
- 1.2 Volt

Blocks simulation : spectre
 Top level simulation : AMS & behaviour



Schematic « top level »

- « Génération automatique »
- Dimensions ~ 1.0 mm x 1.0 mm

Rcarré (M1) : 0.16 Ohms

Rcarré (M9) : 0.0218 Ohms

capa (M1) : 0.16 Ohms

capa (M9) : 0.0218 Ohms

Métal (400fF / mm) 20 mm \equiv 8pF ;

1 mm \equiv 50 Ω (pour la clk attention au jitter)

1ns \equiv 1mA ; invD24 : 3mA

Vth = 0.450 V

Tox = 2.6 nm

(fast corner, 1.6V/-55C)

Final integration : Conf Column Chip ; C3

Blocks simulation : spectre

Top level simulation : AMS & behaviour

Supply Voltage

1.2V \pm 10%

3 metal stacks

6+1 metals (“base metal stack”)

4-thin, 1-thick, 1-UTM, RDL

7+1 metals (“CMS MPA metal stack”)

5-thin, 1-thick, 1-UTM, RDL

available on special request

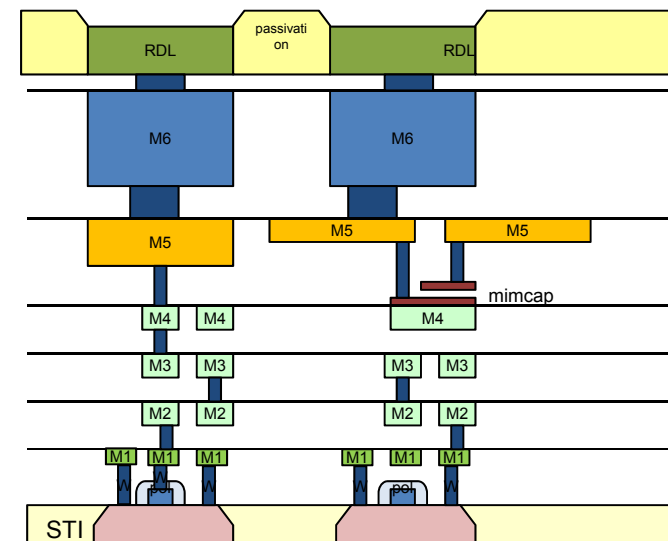
9+1 metals (compatible with mini@sic)

7-thin, 1-thick, 1-UTM, RDL

Note: 220 k\$ NRE price adder

with respect to base metal stack (!)

1-Ultra-Thick Metal. Last metal, redistribution layer (RDL)



Quelques dates clés

- Juin 14 : Pré étude microélectronique pixel (t=0)
 - 3 juillet 14: **Non Disclosure Agreement** Kit TSMC 65nm pour signature
 - 5 sept. 14 : Proposal collaboration RD53 (soumission)
 - 15 déc. 14 : 1^{ère} rencontre avec Jorgen Christiansen (responsable RD53)
 - janv. 15 : Guest RD53 & 1^{ère} rencontre avec R.Beccherle (responsable WG IO)
 - 30 janv. 15: Access Repository FEI-4 (uvm , codes)
 - Mai 15 : Etude code RTL chargement configuration FEI-4
 - 15 juin 15 : NDA signé
 - Juillet 15 : Synthèse, P&R d'une Double Colonne de chargement
 - Août 15 : Etude de la partie I/O du FEI4
 - 28 oct. 15 : Kit TSMC 65nm installé
 - 28 oct. 15 : Collaboration CPPM (officialisée)
 - 13 nov. 15 : Réception 1^{ère} version des Latch CPPM
 - 11 janv. 16 : Réception Latch CPPM (version finale)
 - 4 mars 16 : Présentation puce C3 LAL à Jorgen Christiansen
 - 10 mars 16 : Run Multi-Project Wafer (prix & réservation)
 - 21 mars : Correction des PADs (Bibliothèques PADs OK)
 - 23 mars 16 : (1^{ère}) soumission
 - 31 mars 16 : envoi du GDS (2^{ème} soumission)
 - 5 avril 16 : confirme le GDS (tape-out) -> fonderie.
-
- 13 avril 16 : entretien avec R. Beccherle (meeting RD53)
 - 26 avril 16 : Participation au meeting RD53-A



Groupe ATLAS

